ELSEVIER

Applied Surface Science 96–98 (1996) 891–901

applied surface science

Author index

Abert, A., J.P. Contour, A. Défossez, D. Ravelosona, W. Schwegle and P. Ziemann, Critical thickness of YBaCuO (123) strained thin films and superlattices grown by pulsed laser deposition 96–98 (1996) 703
Acquaviva, S., see Berling, D. 96–98 (1996) 739
Aden, M. and E.W. Kreutz, Material removal and plasmadynamics during pulsed laser deposition by excimer and CO_2 laser radiation 96–98 (1996) 39
Aden, M., see Alunovic, M. 96–98 (1996) 222
Afif, M., J.P. Girardeau-Montaut, C. Tomas, M. Romand, M. Charbonnier, N.S. Prakash, A. Perez, G. Marest and J.M. Frigerio, In situ surface cleaning of pure and implanted tungsten photocathodes by pulsed laser irradiation 96–98 (1996) 469
Afonso, C.N., J.M. Ballesteros, J. Gonzalo, G.C. Righini and S. Pelli, Rare-earth doped glass waveguides prepared by pulsed laser deposition 96–98 (1996) 760
Afonso, C.N., see Gonzalo, J. 96–98 (1996) 693
Aguiar, R., F. Sánchez and M. Varela, Single crystal laser patterning for selective $YBa_2Cu_3O_{7-x}$ growth 96–98 (1996) 405
Aguiar, R., see Polo, M.C. 96–98 (1996) 870
Akhsakhalyan, A.D., see Gorbunov, A.A. 96–98 (1996) 649
Al-Wazzan, R.A., J.M. Hendron and T. Morrow, Spatially and temporally resolved emission intensities and number densities in low temperature laser-induced plasmas in vacuum and in ambient gases 96–98 (1996) 170
Al-Wazzan, R.A., see Hendron, J.M. 96–98 (1996) 112
Alexandrescu, R., see Leggieri, G. 96–98 (1996) 866
Alfonso, J.E., M.J. Martín, J. Mendiola, K. Polgár and C. Zaldo, Pulsed laser deposition of sillenite films intended for photorefractive damage free waveguides 96–98 (1996) 791
Aliouchouche, A., see Débarre, D. 96–98 (1996) 453
Allegrini, M., see Fuso, F. 96–98 (1996) 181
Alunovic, M., H. Stamm, M. Aden and E.W. Kreutz, Optical and particle properties of PLD vapour/plasmas of ceramics 96–98 (1996) 222
Amodeo, A., see Amoruso, S. 96–98 (1996) 175
Amoruso, S., A. Amodeo, V. Berardi, R. Bruzzese, N. Spinelli and R. Velotta, Laser produced plasmas in high fluence ablation of metallic surfaces probed by time-of-flight mass spectrometry 96–98 (1996) 175
An, C.W., see Mertin, M. 96–98 (1996) 842
Anderson, J., see Boardman, A.D. 96–98 (1996) 55
Andrei, A., see Verardi, P. 96–98 (1996) 827
Angleraud, B., C. Girault, C. Champeaux, F. Garrelie, C. Germain and A. Catherinot, Study of the expansion of the laser ablation plume above a boron nitride target 96–98 (1996) 117
Anisimov, S.I., B.S. Luk'yanchuk and A. Luches, An analytical model for three-dimensional laser plume expansion into vacuum in hydrodynamic regime 96–98 (1996) 24
Antoni, F., C. Fuchs and E. Fogarassy, Analytical description of the film thickness distribution obtained by the pulsed laser ablation of a monoatomic target: application to silicon and germanium 96–98 (1996) 50
Aoki, K., see Togashi, H. 96–98 (1996) 267
Aoki, Y., see Maruyama, K. 96–98 (1996) 764
Arimondo, E., see Fuso, F. 96–98 (1996) 181
Arnold, W., see Hoffmann, A. 96–98 (1996) 71
Autric, M., see Grangeon, F. 96–98 (1996) 186
Autric, M., see Movtchan, I.A. 96–98 (1996) 251
Autric, M., see Nicolas, G. 96–98 (1996) 296

Baeri, P., see Reitano, R. 96–98 (1996) 302
Ballesteros, J.M., see Afonso, C.N. 96–98 (1996) 760
Baptista, J.L., see Gomes, M.J.M. 96–98 (1996) 779
Barborica, A., see Leggieri, G. 96–98 (1996) 866
Barthe, M.F., C. Perrin, L. Vivet, B. Dubreuil and T. Gibert, Laser induced nitridation of Ga on GaAs surfaces 96–98 (1996) 359
Barthe, M.F., see Vivet, L. 96–98 (1996) 238
Bäuerle, D., see Proyer, S. 96–98 (1996) 668
Bäuerle, D., see Li, S.T. 96–98 (1996) 713
Bäuerle, D., see Ritzer, A. 96–98 (1996) 721
Bäuerle, D., see Stangl, E. 96–98 (1996) 731
Beauvois, S., see Viville, P. 96–98 (1996) 558
Becker, W., see Geiger, M. 96–98 (1996) 309

Belouet, C., Thin film growth by the pulsed laser assisted deposition technique 96–98 (1996) 630
Bennett, L.S., see Lippert, T. 96–98 (1996) 601
Berardi, V., see Amoruso, S. 96–98 (1996) 175
Bergmann, H.W., Excimer laser induced surface modifications and matter interaction using double-pulse-technique (DPT) 96–98 (1996) 287
Bergt, M., see Götz, T. 96–98 (1996) 280
Berling, D., A. Del Vecchio, S. Acquaviva, D. Bolmont, G. Leggieri, B. Loegel, M. Luisa De Giorgi, A. Luches, A. Mehdaoui and L. Tapfer, Reactive laser deposition of high quality YBaCuO and ErBaCuO films 96–98 (1996) 739
Bertóti, I., see Szörényi, T. 96–98 (1996) 363
Beserman, R., see Chergui, A. 96–98 (1996) 874
Betz, G., see Seifert, N. 96–98 (1996) 33
Bigl, F., see Zimmer, K. 96–98 (1996) 425
Bjormander, C., see Tyunina, M. 96–98 (1996) 831
Blank, D.H.A., A.J.H.M. Rijnders, F.J.G. Roesthuis, G. den Ouden and H. Rogalla, Improved properties of Pulsed Laser Deposited YBaCuO on $NdGaO_3$ using CeO_2 template layers 96–98 (1996) 685
Blaschke, H., see Welsch, E. 96–98 (1996) 393
Blom, P.W.M., see Cillessen, J.F.M. 96–98 (1996) 744
Boardman, A.D., B. Cresswell and J. Anderson, An analytical model for the laser ablation of materials 96–98 (1996) 55
Boher, P., J.L. Stehle, M. Stehle and B. Godard, Single shot excimer laser annealing of amorphous silicon for AMLCD 96–98 (1996) 376
Bolmont, D., see Berling, D. 96–98 (1996) 739
Boquillon, J.P., see Oltra, R. 96–98 (1996) 484
Bor, Zs., see Hopp, B. 96–98 (1996) 611
Borz, M., see Proyer, S. 96–98 (1996) 668
Boulmer, J., see Débarre, D. 96–98 (1996) 453
Bourguignon, B., see Débarre, D. 96–98 (1996) 453
Boyd, I.W., see Tyrrell, G.C. 96–98 (1996) 227
Boyd, I.W., see Zhang, J.-Y. 96–98 (1996) 399
Boyd, I.W., see Tyrrell, G.C. 96–98 (1996) 769
Boyd, I.W., see Coccia, L.G. 96–98 (1996) 795
Boyd, I.W., see King, S.L. 96–98 (1996) 811
Bradley, R.A., see Hess, W.P. 96–98 (1996) 321
Brédas, J.L., see Viville, P. 96–98 (1996) 558
Broulik, U., see Reisse, G. 96–98 (1996) 752
Bruzzese, R., see Amoruso, S. 96–98 (1996) 175
Budai, J.D., see Norton, D.P. 96–98 (1996) 672
Budin, J.P., see Débarre, D. 96–98 (1996) 453
Bulgakov, A.V., M.R. Predtechensky and A.P. Mayorov, Transport of neutral atoms, monoxides and clusters in the plume produced by laser ablation of $YBa_2Cu_3O_{7-x}$ in oxygen environment 96–98 (1996) 159
Burmester, S., see Metev, S. 96–98 (1996) 122
Caetano, M., see Mao, X. 96–98 (1996) 126
Caetano, M., see Russo, R.E. 96–98 (1996) 144
Cagan, V., see Lisfi, A. 96–98 (1996) 66
Cagan, V., see Guyot, M. 96–98 (1996) 802
Calvo, B., see Gobernado-Mitre, I. 96–98 (1996) 474
Campbell, E.E.B., see Rosenfeld, A. 96–98 (1996) 439
Caron, M., see Lecours, A. 96–98 (1996) 341
Catherinot, A., see Angleraud, B. 96–98 (1996) 117
Catherinot, A., see Champeaux, C. 96–98 (1996) 775
Catherinot, A., see Garapon, C. 96–98 (1996) 836
Caudano, R., see Girardeaux, C. 96–98 (1996) 586
Chakoumakos, B.C., see Norton, D.P. 96–98 (1996) 672
Champeaux, C., P. Marchet and A. Catherinot, Epitaxial ferroelectric PZT and BST thin films by pulsed UV laser deposition 96–98 (1996) 775
Champeaux, C., see Angleraud, B. 96–98 (1996) 117
Champeaux, C., see Garapon, C. 96–98 (1996) 836
Chan, W.-T., see Mao, X. 96–98 (1996) 126
Charbonnier, M., see Afif, M. 96–98 (1996) 469
Chater, R.J., see Coccia, L.G. 96–98 (1996) 795
Chen, K.R., J.N. Leboeuf, R.F. Wood, D.B. Geohegan, J.M. Donato, C.L. Liu and A.A. Puretzky, Laser–solid interaction and dynamics of laser-ablated materials 96–98 (1996) 45
Chen, K.R., see Leboeuf, J.N. 96–98 (1996) 14
Chen, Y., see Ding, D. 96–98 (1996) 581
Cheng, H.F., see Huang, C.S. 96–98 (1996) 735
Chergui, A., J.L. Deiss, J.B. Grun, J.L. Loison, M. Robino and R. Beserman, Structural and optical characteristics of pulsed laser deposited ZnSe epilayers 96–98 (1996) 874
Chung, B.C., C.H. Tsai, S.S. Hsu, C.S. Huang, T.Y. Tseng and I.N. Lin, Spectroscopic study of the microwave plasma enhanced pulsed laser deposition for $Y_1Ba_2Cu_3O_{7-x}$ superconducting thin films 96–98 (1996) 233
Chung, B.C., see Huang, C.S. 96–98 (1996) 735
Cillessen, J.F.M., R.M. Wolf, J.B. Giesbers, P.W.M. Blom, K.-O. Grosse-Holz and E. Pastoor, Growth, structuring and characterisation of all-oxide thin film devices prepared by pulsed laser deposition 96–98 (1996) 744
Cillessen, J.F.M., see Grosse-Holz, K.-O. 96–98 (1996) 784
Ciureanu, P., see Lecours, A. 96–98 (1996) 341
Clèries, L., see Serra, P. 96–98 (1996) 216
Clèries, L., see Polo, M.C. 96–98 (1996) 870
Coccia, L.G., G.C. Tyrrell, J.A. Kilner, D. Waller, R.J. Chater and I.W. Boyd, Pulsed laser deposition of novel materials for thin film solid oxide fuel cell applications: $Ce_{0.9}Gd_{0.1}O_{1.95}$, $La_{0.7}Sr_{0.3}CoO_y$ and $La_{0.7}Sr_{0.3}Co_{0.2}Fe_{0.8}O_y$ 96–98 (1996) 795
Coccia, L.G., see Tyrrell, G.C. 96–98 (1996) 227
Coccia, L.G., see Tyrrell, G.C. 96–98 (1996) 769

Contour, J.P., see Abert, A. 96–98 (1996) 703
Cordier, P., see Dauscher, A. 96–98 (1996) 410
Cranton, W.M., P.H. Key, D. Sands, C.B. Thomas and F.X. Wagner, XeCl laser ablation of thin film ZnS 96–98 (1996) 501
Cresswell, B., see Boardman, A.D. 96–98 (1996) 55
Cruz, F., see Oltra, R. 96–98 (1996) 484
Csete, M., see Hopp, B. 96–98 (1996) 611
Currie, J.F., see Lecours, A. 96–98 (1996) 341
Currie, J.F., see Izquierdo, R. 96–98 (1996) 855

Dam, B., J.H. Rector, J. Johansson, S. Kars and R. Griessen, Stoichiometric transfer of complex oxides by pulsed laser deposition 96–98 (1996) 679
Dauscher, A., V. Feregotto, P. Cordier and A. Thomy, Laser induced periodic surface structures on iron 96–98 (1996) 410
Débarre, D., A. Aliouchouche, J. Boulmer, B. Bourguignon and J.P. Budin, The role of gas-phase in the laser etching of Cu by CCl_4 96–98 (1996) 453
Défossez, A., see Abert, A. 96–98 (1996) 703
de Frutos, A.M., see Gobernado-Mitre, I. 96–98 (1996) 474
Deiss, J.L., see Chergui, A. 96–98 (1996) 874
Del Vecchio, A., see Berling, D. 96–98 (1996) 739
de Matos Gomes, E., see Gomes, M.J.M. 96–98 (1996) 779
Deno, H., S. Sugiyama, Y. Kakudate, M. Yoshida and S. Fujiwara, VUV ablation of polymers by emission from gas-puff Z-pinch plasmas 96–98 (1996) 563
den Ouden, G., see Blank, D.H.A. 96–98 (1996) 685
de Wit, L., see Geurtsen, A.J.M. 96–98 (1996) 887
Diaci, J., D. Hurley, J.W. Wagner and J. Možina, Simultaneous monitoring of ablative shocks in air by high-speed cineholography and multiple-pass beam deflection probe 96–98 (1996) 154
Dickinson, J.T., J.-J. Shin and S.C. Langford, The role of defects in laser induced positive ion emission from ionic crystals 96–98 (1996) 316
Dickinson, J.T., J.J. Shin and S.C. Langford, Laser-induced emission of neutral atoms and molecules from electron-irradiated $NaNO_3$ 96–98 (1996) 326
Dickinson, J.T., see Norton, M.G. 96–98 (1996) 617
Dietsch, R., see Panzner, M. 96–98 (1996) 643
Dietsch, R., see Gorbunov, A.A. 96–98 (1996) 649
Dimova-Malinovska, D., M. Tzolov, N. Malinowski, Ts. Marinova and V. Krastev, Laser-induced formation of visible light emitting silicon 96–98 (1996) 457
Dinescu, M., see Verardi, P. 96–98 (1996) 827
Ding, D., T. Käämbre, S. Ljungström, Y. Chen, K. Siegbahn, E. Wistus, P. Swensson and E. Mukhtar, Mapping of molecular C_{17} indandione-1,3 pyridinium betaine adsorbates on fused silica by surface second harmonic generation 96–98 (1996) 581
Dolgaev, S.I., A.A. Lyalin, A.V. Simakin and G.A. Shafeev, Fast etching of sapphire by a visible range quasi-cw laser radiation 96–98 (1996) 491
Donato, J.M., see Leboeuf, J.N. 96–98 (1996) 14
Donato, J.M., see Chen, K.R. 96–98 (1996) 45
Dreyfus, R.W., see Le, H.C. 96–98 (1996) 76
Dreyfus, R.W., see Le, H.C. 96–98 (1996) 164
Dreyfus, R.W., see Movtchan, I.A. 96–98 (1996) 251
Drilhole, D., see Lazare, S. 96–98 (1996) 605
Dubreuil, B., see Vivet, L. 96–98 (1996) 238
Dubreuil, B., see Barthe, M.F. 96–98 (1996) 359
Dyer, P.E., D.M. Karnakis, P.H. Key and P. Monk, Excimer laser ablation for micro-machining: geometric effects 96–98 (1996) 415
Dyer, P.E., R.J. Farley, R. Giedl and D.M. Karnakis, Excimer laser ablation of polymers and glasses for grating fabrication 96–98 (1996) 537
Dyer, P.E., D.M. Karnakis, P.H. Key and J.P. Tait, Excimer laser ablation of low and high absorption index polymers 96–98 (1996) 596
Dyer, P.E., S.R. Jackson, P.H. Key, W.J. Metheringham and M.J.J. Schmidt, Excimer laser ablation and film deposition of Ti:sapphire 96–98 (1996) 849

Ehring, H. and B.U.R. Sundqvist, Excited state relaxation processes of MALDI-matrices studied by luminescence spectroscopy 96–98 (1996) 577
Ellegaard, O., see Svendsen, W. 96–98 (1996) 518
Enard, J.P., see Pérez Casero, R. 96–98 (1996) 697
Engel, Th., see Stauter, C. 96–98 (1996) 522
Esrom, H., see Zhang, J.-Y. 96–98 (1996) 399
Esteve, J., see Polo, M.C. 96–98 (1996) 870
Ettrich, K., see Welsch, E. 96–98 (1996) 393

Fähler, S. and H.-U. Krebs, Calculations and experiments of material removal and kinetic energy during pulsed laser ablation of metals 96–98 (1996) 61
Falkner, B., see Ritzer, A. 96–98 (1996) 721
Farley, R.J., see Dyer, P.E. 96–98 (1996) 537
Feregotto, V., see Dauscher, A. 96–98 (1996) 410
Flamant, G., see Mazhukin, V.I. 96–98 (1996) 82
Flamant, G., see Mazhukin, V.I. 96–98 (1996) 89
Flamant, G., see Gnedovets, A.G. 96–98 (1996) 272
Flamant, G., see Ignatiev, M.B. 96–98 (1996) 505
Fogarassy, E., see Antoni, F. 96–98 (1996) 50
Fontaine, J., see Stauter, C. 96–98 (1996) 522
Frigerio, J.M., see Afif, M. 96–98 (1996) 469
Fuchs, C., see Antoni, F. 96–98 (1996) 50
Fujii, T., S. Inoue and F. Kannari, Deposition of fluoropolymer thin films contain-

ing semiconductor microcrystallites by VUV laser ablation 96–98 (1996) 621
Fujii, T., H. Shima, N. Matsumoto and F. Kannari, Electrical and optical characteristics of organic thin films fabricated by laser ablation 96–98 (1996) 625
Fujimoto, R., see Inoue, N. 96–98 (1996) 656
Fujiwara, S., see Deno, H. 96–98 (1996) 563
Fukumura, H., Y. Kohji and H. Masuhara, Laser implantation of fluorescent molecules into polymer films 96–98 (1996) 569
Fuso, F., L.N. Vyacheslavov, G. Lorenzi, M. Allegrini and E. Arimondo, Optical diagnostics of the laser–target and laser–plume interaction in pulsed laser ablation 96–98 (1996) 181

Gaponov, S.V., see Gorbunov, A.A. 96–98 (1996) 649
Garapon, C., C. Champeaux, J. Mugnier, G. Panczer, P. Marchet, A. Catherinot and B. Jacquier, Preparation of TiO_2 thin films by pulsed laser deposition for waveguiding applications 96–98 (1996) 836
García, C., J. Ramos, A.C. Prieto, J. Jiménez, C. Geertsen, J.L. Lacour and P. Mauchien, Micro-Raman study of UV laser ablation of GaAs and Si substrates 96–98 (1996) 370
Gardeniers, J.G.E., see King, S.L. 96–98 (1996) 811
Garrelie, F., see Angleraud, B. 96–98 (1996) 117
Geertsen, C., see García, C. 96–98 (1996) 370
Geiger, M., W. Becker, T. Rebhan, J. Hutfless and N. Lutz, Increase of efficiency for the XeCl excimer laser ablation of ceramics 96–98 (1996) 309
Geohegan, D.B. and A.A. Puretzky, Laser ablation plume thermalization dynamics in background gases: combined imaging, optical absorption and emission spectroscopy, and ion probe measurements 96–98 (1996) 131
Geohegan, D.B., see Leboeuf, J.N. 96–98 (1996) 14
Geohegan, D.B., see Chen, K.R. 96–98 (1996) 45
Geohegan, D.B., see Puretzky, A.A. 96–98 (1996) 859
Geretovszky, Zs., see Szörényi, T. 96–98 (1996) 363
Germain, C., see Angleraud, B. 96–98 (1996) 117
German, K.A.H., see Hess, W.P. 96–98 (1996) 321
Geurtsen, A.J.M., J.C.S. Kools, L. de Wit and J.C. Lodder, Pulsed Laser Deposition of permanent magnetic $Nd_2Fe_{14}B$ thin films 96–98 (1996) 887
Giardini Guidoni, A., see Mele, A. 96–98 (1996) 102
Gibert-Legrand, T., see Vivet, L. 96–98 (1996) 238
Gibert, T., see Barthe, M.F. 96–98 (1996) 359
Giedl, R., see Dyer, P.E. 96–98 (1996) 537
Giesbers, J.B., see Cillessen, J.F.M. 96–98 (1996) 744
Girardeau-Montaut, J.P., see Afif, M. 96–98 (1996) 469
Girardeaux, C., Y. Idrissi, J.J. Pireaux and R. Caudano, Etching and functionalization of a fluorocarbon polymer by UV laser treatment 96–98 (1996) 586
Girault, C., see Angleraud, B. 96–98 (1996) 117
Gnedovets, A.G., E.B. Kul'batskii, I. Smurov and G. Flamant, Particles synthesis in erosive laser plasma in a high pressure atmosphere 96–98 (1996) 272
Gobernado-Mitre, I., J. Medina, B. Calvo, A.C. Prieto, L.A. Leal, B. Pérez, F. Marcos and A.M. de Frutos, Laser cleaning in art restoration 96–98 (1996) 474
Godard, B., see Boher, P. 96–98 (1996) 376
Goerke, F., A. Thorns and U. Merkt, Laser deposition of $YBa_2Cu_3O_7$ films on MgO(100) at 100 mm target–substrate distance and oxygen pressures below 0.1 mbar 96–98 (1996) 708
Gogoll, S., E. Stenzel, M. Reichling, H. Johansen and E. Matthias, Laser damage of $CaF_2(111)$ surfaces at 248 nm 96–98 (1996) 332
Gomes, M.J.M., E. de Matos Gomes, P.L.Q. Mantas and J.L. Baptista, Growth and characterization of PLZT films 96–98 (1996) 779
Gómez San Roman, R., see Gonzalo, J. 96–98 (1996) 693
Gómez San Román, R., see Pérez Casero, R. 96–98 (1996) 697
Gonzalo, J., C.N. Afonso, J. Perrière and R. Gómez San Roman, The importance of gas scattering processes on the stoichiometry deviations of laser deposited films 96–98 (1996) 693
Gonzalo, J., see Afonso, C.N. 96–98 (1996) 760
Gorbach, T.Ya., M. Kuźma, E. Sheregii, P.S. Smertenko, S.V. Svechnikov and G. Wisz, Deposition of HgCdTe epitaxial layers on anisotropically etched silicon surfaces by laser evaporation 96–98 (1996) 881
Gorbunov, A.A., W. Pompe, A. Sewing, S.V. Gaponov, A.D. Akhsakhalyan, I.G. Zabrodin, I.A. Kas'kov, E.B. Klyenkov, A.P. Morozov, N.N. Salaschenko, R. Dietsch, H. Mai and S. Völlmar, Ultrathin film deposition by pulsed laser ablation using crossed beams 96–98 (1996) 649
Götz, T., M. Bergt, W. Hoheisel, F. Träger and M. Stuke, Laser ablation of metals: the transition from non-thermal processes to thermal evaporation 96–98 (1996) 280
Grad, L. and J. Možina, Optodynamic studies of Er:YAG laser induced microexplosions in dentin 96–98 (1996) 591
Graham, W.G., see Hendron, J.M. 96–98 (1996) 112
Grangeon, F., H. Sassoli, W. Marine and M. Autric, Time-of-flight characterization of laser ablation plume from $NbTe_2$ target in He atmosphere 96–98 (1996) 186
Granse, G., S. Völlmar, A. Lenk, A. Rupp and K. Rohr, Modeling of laser induced

plasma, spectroscopic and time of flight experiments in pulsed laser deposition 96–98 (1996) 97
Granse, G., see Lenk, A. 96–98 (1996) 195
Grätz, M., C. Tillman, I. Mercer and S. Svanberg, X-ray generation for medical applications from a laser-produced plasma 96–98 (1996) 443
Griessen, R., see Dam, B. 96–98 (1996) 679
Grosse-Holz, K.-O., J.F.M. Cillessen and R. Waser, Electrical characterization of semiconducting La doped $SrTiO_3$ thin films prepared by pulsed laser deposition 96–98 (1996) 784
Grosse-Holz, K.-O., see Cillessen, J.F.M. 96–98 (1996) 744
Grun, J.B., see Chergui, A. 96–98 (1996) 874
Guan, W., see Lazare, S. 96–98 (1996) 605
Gusev, I.V., see Mazhukin, V.I. 96–98 (1996) 82
Guyot, M., A. Lisfi, R. Krishnan, M. Porte, P. Rougier and V. Cagan, Ferrimagnetic thin films prepared by pulsed laser deposition 96–98 (1996) 802
Guyot, M., see Lisfi, A. 96–98 (1996) 66
Gyorgy, E., see Leggieri, G. 96–98 (1996) 866

Habermeier, H.-U., N. Jisrawi and G. Jäger-Waldau, Giant laser-induced voltages at room temperature in Pr doped Y–Ba–Cu–O thin films 96–98 (1996) 689
Haglund, Jr., R.F., Microscopic and mesoscopic aspects of laser-induced desorption and ablation 96–98 (1996) 1
Hanus, F., A. Jadin and L.D. Laude, Pulsed laser deposition of high quality ITO thin films 96–98 (1996) 807
Hanus, F., see Izquierdo, R. 96–98 (1996) 855
Heimann, R.B., see Kokai, F. 96–98 (1996) 261
Hellebrand, B., see Stangl, E. 96–98 (1996) 731
Hendron, J.M., R.A. Al-Wazzan, C. Mahony, T. Morrow and W.G. Graham, Electrostatic probe and optical spectroscopy studies of low temperature laser produced plasmas 96–98 (1996) 112
Hendron, J.M., see Al-Wazzan, R.A. 96–98 (1996) 170
Hess, W.P., K.A.H. German, R.A. Bradley and M.I. McCarthy, Laser ablation of sodium nitrate: NO desorption following excitation of the π–π^* band of the nitrate anion 96–98 (1996) 321
Hipps, K.W., see Norton, M.G. 96–98 (1996) 617
Hiroshima, Y., see Maruyama, K. 96–98 (1996) 764
Hirsch, D., see Zimmer, K. 96–98 (1996) 425
Hoffmann, A. and W. Arnold, Calculation and measurement of the ultrasonic signals generated by ablating material with a Q-switched pulse laser 96–98 (1996) 71
Hoheisel, W., see Götz, T. 96–98 (1996) 280
Holz, Th., see Panzner, M. 96–98 (1996) 643
Hopp, B., M. Csete, K. Révész, J. Vinkó and Zs. Bor, Formation of the surface structure of polyethylene-terephtalate (PET) due to ArF excimer laser ablation 96–98 (1996) 611
Hsu, S.S., see Chung, B.C. 96–98 (1996) 233
Huang, C.S., T.Y. Tseng, B.C. Chung, C.H. Tsai, H.F. Cheng and I.N. Lin, Mirror-smooth $YBa_2Cu_3O_{7-x}$ superconducting films deposited by plasma-enhanced pulsed laser deposition technique 96–98 (1996) 735
Huang, C.S., see Chung, B.C. 96–98 (1996) 233
Hurley, D., see Diaci, J. 96–98 (1996) 154
Husinsky, W., see Seifert, N. 96–98 (1996) 33
Hutfless, J., see Geiger, M. 96–98 (1996) 309

Idrissi, Y., see Girardeaux, C. 96–98 (1996) 586
Ignatiev, M., see Titov, V. 96–98 (1996) 387
Ignatiev, M.B., I.Yu. Smurov, G. Flamant and V.N. Senchenko, Surface temperature measurements during pulsed laser action on metallic and ceramic materials 96–98 (1996) 505
Inoue, N., S. Kashiwabara, S. Toshima and R. Fujimoto, Off-axis excimer laser deposition of Ta_2O_5 thin films 96–98 (1996) 656
Inoue, S., see Fujii, T. 96–98 (1996) 621
Ivanov, D., see Lecours, A. 96–98 (1996) 341
Ivanov, D., see Izquierdo, R. 96–98 (1996) 855
Izquierdo, R., F. Hanus, Th. Lang, D. Ivanov, M. Meunier, L. Laude, J.F. Currie and A. Yelon, Pulsed laser deposition of nasicon thin films 96–98 (1996) 855

Jackson, S.R., see Dyer, P.E. 96–98 (1996) 849
Jacquier, B., see Garapon, C. 96–98 (1996) 836
Jadin, A., see Hanus, F. 96–98 (1996) 807
Jäger-Waldau, G., see Habermeier, H.-U. 96–98 (1996) 689
Jellison Jr., G.E., see Puretzky, A.A. 96–98 (1996) 859
Jiang, W., see Norton, M.G. 96–98 (1996) 617
Jiménez, J., see García, C. 96–98 (1996) 370
Jisrawi, N., see Habermeier, H.-U. 96–98 (1996) 689
Johansen, H., see Gogoll, S. 96–98 (1996) 332
Johansson, J., see Dam, B. 96–98 (1996) 679

Käämbre, T., see Ding, D. 96–98 (1996) 581
Kabashin, A.V., W. Marine, P.I. Nikitin and M. Sentis, Electromagnetic diagnostics during pulsed laser deposition 96–98 (1996) 139
Kaiser, N., see Welsch, E. 96–98 (1996) 393
Kakudate, Y., see Deno, H. 96–98 (1996) 563
Kameyama, T., see Togashi, H. 96–98 (1996) 267
Kannari, F., see Fujii, T. 96–98 (1996) 621
Kannari, F., see Fujii, T. 96–98 (1996) 625
Kántor, Z., see Szörényi, T. 96–98 (1996) 363
Karnakis, D.M., see Dyer, P.E. 96–98 (1996) 415
Karnakis, D.M., see Dyer, P.E. 96–98 (1996) 537
Karnakis, D.M., see Dyer, P.E. 96–98 (1996) 596
Kars, S., see Dam, B. 96–98 (1996) 679
Kashiwabara, S., see Inoue, N. 96–98 (1996) 656

Kas'kov, I.A., see Gorbunov, A.A. 96–98 (1996) 649
Kautek, W., see Krüger, J. 96–98 (1996) 430
Keiper, B., see Reisse, G. 96–98 (1996) 752
Kelly, R. and A. Miotello, Comments on explosive mechanisms of laser sputtering 96–98 (1996) 205
Kelly, R., see Mele, A. 96–98 (1996) 102
Key, P.H., see Dyer, P.E. 96–98 (1996) 415
Key, P.H., see Cranton, W.M. 96–98 (1996) 501
Key, P.H., see Dyer, P.E. 96–98 (1996) 596
Key, P.H., see Dyer, P.E. 96–98 (1996) 849
Kilner, J.A., see Coccia, L.G. 96–98 (1996) 795
King, S.L., J.G.E. Gardeniers and I.W. Boyd, Pulsed-laser deposited ZnO for device applications 96–98 (1996) 811
Klyenkov, E.B., see Gorbunov, A.A. 96–98 (1996) 649
Koga, Y., see Kokai, F. 96–98 (1996) 261
Koga, Y., see Togashi, H. 96–98 (1996) 267
Kohji, Y., see Fukumura, H. 96–98 (1996) 569
Kokai, F., Y. Koga and R.B. Heimann, Magnetic field enhanced growth of carbon cluster ions in the laser ablation plume of graphite 96–98 (1996) 261
Kolev, K., see Viville, P. 96–98 (1996) 558
Kools, J.C.S., see Geurtsen, A.J.M. 96–98 (1996) 887
Kopač, S., J. Pirš and J. Možina, Optodynamics of laser ablation of graduation lines in chromium thin film on glass 96–98 (1996) 420
Kotlyarchuk, B.K., D.I. Popovych, V.K. Savchuk and V.G. Savitsky, Investigation of vaporization and condensation processes of thin layers of CdHgTe from laser erosion plasma in Hg atmosphere 96–98 (1996) 192
Krabbe, A., see Streller, U. 96–98 (1996) 448
Krastev, V., see Dimova-Malinovska, D. 96–98 (1996) 457
Krebs, H.-U., see Fähler, S. 96–98 (1996) 61
Kreutz, E.W., see Aden, M. 96–98 (1996) 39
Kreutz, E.W., see Alunovic, M. 96–98 (1996) 222
Kreutz, E.W., see Wesner, D.A. 96–98 (1996) 479
Kreutz, E.W., see Pfleging, W. 96–98 (1996) 496
Kreutz, E.W., see Mertin, M. 96–98 (1996) 842
Krishnan, R., see Lisfi, A. 96–98 (1996) 66
Krishnan, R., see Guyot, M. 96–98 (1996) 802
Krüger, J. and W. Kautek, Femtosecond-pulse visible laser processing of transparent materials 96–98 (1996) 430
Kuba, K. and T. Sugihara, Selection of kinetic energy of laser ablated particles 96–98 (1996) 659
Kul'batskii, E.B., see Gnedovets, A.G. 96–98 (1996) 272
Kuźma, M., see Gorbach, T.Ya. 96–98 (1996) 881

Lacour, J.L., see García, C. 96–98 (1996) 370
Lambin, G., see Viville, P. 96–98 (1996) 558
Lang, Th., see Izquierdo, R. 96–98 (1996) 855
Langford, S.C., see Dickinson, J.T. 96–98 (1996) 316
Langford, S.C., see Dickinson, J.T. 96–98 (1996) 326
Laude, L., see Viville, P. 96–98 (1996) 558
Laude, L., see Izquierdo, R. 96–98 (1996) 855
Laude, L.D., see Szörényi, T. 96–98 (1996) 363
Laude, L.D., see Hanus, F. 96–98 (1996) 807
Lazare, S., W. Guan and D. Drilhole, High sensitivity quadrupole mass spectrometry of neutrals sputtered by UV-laser ablation of polymers 96–98 (1996) 605
Lazzaroni, R., see Viville, P. 96–98 (1996) 558
Le, H.C., J. Vuillon, D. Zeitoun, W. Marine, M. Sentis and R.W. Dreyfus, 2D modeling of laser-induced plume expansion near the plasma ignition threshold 96–98 (1996) 76
Le, H.C., R.W. Dreyfus, W. Marine, M. Sentis and I.A. Movtchan, Temperature measurements during laser ablation of Si into He, Ar and O_2 96–98 (1996) 164
Le, H.C., see Movtchan, I.A. 96–98 (1996) 251
Leal, L.A., see Gobernado-Mitre, I. 96–98 (1996) 474
Leboeuf, J.N., K.R. Chen, J.M. Donato, D.B. Geohegan, C.L. Liu, A.A. Puretzky and R.F. Wood, Modeling of dynamical processes in laser ablation 96–98 (1996) 14
Leboeuf, J.N., see Chen, K.R. 96–98 (1996) 45
Lecours, A., M. Caron, P. Ciureanu, G. Turcotte, D. Ivanov, A. Yelon and J.F. Currie, Laser patterning of thin-film electrochemical gas sensors 96–98 (1996) 341
Leggieri, G., A. Luches, M. Martino, A. Perrone, R. Alexandrescu, A. Barborica, E. Gyorgy, I.N. Mihailescu, G. Majni and P. Mengucci, Laser reactive ablation deposition of silicon carbide films 96–98 (1996) 866
Leggieri, G., see Berling, D. 96–98 (1996) 739
Lenk, A., Th. Witke and G. Granse, Density and electron temperature of laser induced plasma – a comparison of different investigation methods 96–98 (1996) 195
Lenk, A., see Granse, G. 96–98 (1996) 97
Lewis, C.L.S., see Weaver, I. 96–98 (1996) 663
Li, B., see Streller, U. 96–98 (1996) 448
Li, S.T., A. Ritzer, S. Proyer, E. Stangl, D. Bäuerle and N. Reschauer, Anisotropic resistivity in pulsed-laser deposited $Bi_2Sr_2CaCu_2O_{8+\delta}$ films 96–98 (1996) 713
Li, S.T., see Ritzer, A. 96–98 (1996) 721
Lin, I.N., see Chung, B.C. 96–98 (1996) 233
Lin, I.N., see Huang, C.S. 96–98 (1996) 735
Lippert, T., L.S. Bennett, T. Nakamura, H. Niino and A. Yabe, Single pulse threshold and transmission behaviour of a triazeno-polymer during pulsed UV-laser irradiation 96–98 (1996) 601
Lisfi, A., M. Guyot, R. Krishnan and V. Cagan, Measurement and calculation of the Fe_2O_3 ablation depth 96–98 (1996) 66
Lisfi, A., see Guyot, M. 96–98 (1996) 802
Liu, C.L., see Leboeuf, J.N. 96–98 (1996) 14

Liu, C.L., see Chen, K.R. 96–98 (1996) 45

Liu, J.M., Z.G. Liu, S.N. Zhu, Y.Y. Zhu and N.B. Ming, Excimer laser ablating preparation of $Ba_2NaNb_5O_{15}$ thin films on $KTiOPO_4$ substrate and its guide wave property 96–98 (1996) 819

Liu, Z.G., see Liu, J.M. 96–98 (1996) 819

Ljungström, S., see Ding, D. 96–98 (1996) 581

Lodder, J.C., see Geurtsen, A.J.M. 96–98 (1996) 887

Loegel, B., see Berling, D. 96–98 (1996) 739

Loison, J.L., see Chergui, A. 96–98 (1996) 874

Lorenzi, G., see Fuso, F. 96–98 (1996) 181

Lowndes, D.H., see Norton, D.P. 96–98 (1996) 672

Luches, A., see Anisimov, S.I. 96–98 (1996) 24

Luches, A., see Berling, D. 96–98 (1996) 739

Luches, A., see Leggieri, G. 96–98 (1996) 866

Luisa De Giorgi, M., see Berling, D. 96–98 (1996) 739

Luk'yanchuk, B.S., see Anisimov, S.I. 96–98 (1996) 24

Lupp, F., see Wesner, D.A. 96–98 (1996) 479

Lüthy, W., see Tosin, P. 96–98 (1996) 384

Lutz, N., see Geiger, M. 96–98 (1996) 309

Lyalin, A.A., see Dolgaev, S.I. 96–98 (1996) 491

Mahony, C., see Hendron, J.M. 96–98 (1996) 112

Mai, H., see Panzner, M. 96–98 (1996) 643

Mai, H., see Gorbunov, A.A. 96–98 (1996) 649

Majni, G., see Leggieri, G. 96–98 (1996) 866

Makimura, T. and K. Murakami, Dynamics of silicon plume generated by laser ablation and its chemical reaction 96–98 (1996) 242

Malinowski, N., see Dimova-Malinovska, D. 96–98 (1996) 457

Mann, K., B. Wolff-Rottke and F. Müller, Cleaning of optical surfaces by excimer laser radiation 96–98 (1996) 463

Mantas, P.L.Q., see Gomes, M.J.M. 96–98 (1996) 779

Mao, X., W.-T. Chan, M. Caetano, M.A. Shannon and R.E. Russo, Preferential vaporization and plasma shielding during nano-second laser ablation 96–98 (1996) 126

Mao, X.L., see Russo, R.E. 96–98 (1996) 144

Marchet, P., see Champeaux, C. 96–98 (1996) 775

Marchet, P., see Garapon, C. 96–98 (1996) 836

Marcos, F., see Gobernado-Mitre, I. 96–98 (1996) 474

Maréchal, C., see Pérez Casero, R. 96–98 (1996) 697

Marest, G., see Afif, M. 96–98 (1996) 469

Marine, W., see Le, H.C. 96–98 (1996) 76

Marine, W., see Kabashin, A.V. 96–98 (1996) 139

Marine, W., see Le, H.C. 96–98 (1996) 164

Marine, W., see Grangeon, F. 96–98 (1996) 186

Marine, W., see Movtchan, I.A. 96–98 (1996) 251

Marino, N., see Reitano, R. 96–98 (1996) 302

Marinova, Ts., see Dimova-Malinovska, D. 96–98 (1996) 457

Martín, M.J., C. Zaldo and J. Mendiola, $Pb_{1-x}Ca_xTiO_3$ thin films prepared by laser ablation of ceramic targets 96–98 (1996) 823

Martín, M.J., see Alfonso, J.E. 96–98 (1996) 791

Martino, M., see Leggieri, G. 96–98 (1996) 866

Maruyama, K., Y. Aoki, M. Matsumoto, Y. Hiroshima and H. Ohta, Preparation of SiO_xN_y films by reactive KrF laser ablation 96–98 (1996) 764

Masuhara, H., see Fukumura, H. 96–98 (1996) 569

Matsumoto, M., see Maruyama, K. 96–98 (1996) 764

Matsumoto, N., see Fujii, T. 96–98 (1996) 625

Matthias, E., see Petzoldt, S. 96–98 (1996) 199

Matthias, E., see Gogoll, S. 96–98 (1996) 332

Mauchien, P., see García, C. 96–98 (1996) 370

Mayorov, A.P., see Bulgakov, A.V. 96–98 (1996) 159

Mazhukin, V.I., I.V. Gusev, I. Smurov and G. Flamant, The influence of the electron structure of atoms shells on characteristics of optical breakdown in metal vapour 96–98 (1996) 82

Mazhukin, V.I., I. Smurov and G. Flamant, 2D-simulation of the system: laser beam + laser plasma + target 96–98 (1996) 89

McCarthy, M.I., see Hess, W.P. 96–98 (1996) 321

McGibbon, M.M., see Puretzky, A.A. 96–98 (1996) 859

Medina, J., see Gobernado-Mitre, I. 96–98 (1996) 474

Mehdaoui, A., see Berling, D. 96–98 (1996) 739

Mele, A., A. Giardini Guidoni, R. Kelly, A. Miotello, S. Orlando and R. Teghil, Spatial distribution of laser-ablated material by probing a plasma plume in three dimensions 96–98 (1996) 102

Mendiola, J., see Alfonso, J.E. 96–98 (1996) 791

Mendiola, J., see Martín, M.J. 96–98 (1996) 823

Mengucci, P., see Leggieri, G. 96–98 (1996) 866

Mercer, I., see Grätz, M. 96–98 (1996) 443

Merkt, U., see Goerke, F. 96–98 (1996) 708

Mertin, M., D. Offenberg, C.W. An, D.A. Wesner and E.W. Kreutz, Pulsed laser deposition of electroceramic thin films 96–98 (1996) 842

Mertin, M., see Wesner, D.A. 96–98 (1996) 479

Metev, S., M. Ozegowski, G. Sepold and S. Burmester, Plasma parameters in pulsed laser-plasma deposition of thin films 96–98 (1996) 122

Metheringham, W.J., see Dyer, P.E. 96–98 (1996) 849

Meunier, M., see Izquierdo, R. 96–98 (1996) 855

Mihailescu, I.N., see Leggieri, G. 96–98 (1996) 866

Ming, N.B., see Liu, J.M. 96–98 (1996) 819

Miotello, A., see Mele, A. 96–98 (1996) 102

Miotello, A., see Kelly, R. 96–98 (1996) 205

Monk, P., see Dyer, P.E. 96–98 (1996) 415

Morenza, J.L., see Serra, P. 96–98 (1996) 216

Morozov, A.P., see Gorbunov, A.A. 96–98 (1996) 649

Morrow, T., see Hendron, J.M. 96–98 (1996) 112

Morrow, T., see Al-Wazzan, R.A. 96–98 (1996) 170

Movtchan, I.A., W. Marine, R.W. Dreyfus, H.C. Le, M. Sentis and M. Autric, Optical spectroscopy of emission from Si–SiO_x nanoclusters formed by laser ablation 96–98 (1996) 251

Movtchan, I.A., see Le, H.C. 96–98 (1996) 164

Možina, J., see Diaci, J. 96–98 (1996) 154

Možina, J., see Kopač, S. 96–98 (1996) 420
Možina, J., see Grad, L. 96–98 (1996) 591
Mugnier, J., see Garapon, C. 96–98 (1996) 836
Mukaida, M., see Togashi, H. 96–98 (1996) 267
Mukhtar, E., see Ding, D. 96–98 (1996) 581
Müller, F., see Mann, K. 96–98 (1996) 463
Murakami, K., see Makimura, T. 96–98 (1996) 242

Nakamura, A., see Sugioka, K. 96–98 (1996) 347
Nakamura, T., see Lippert, T. 96–98 (1996) 601
Nicolas, G. and M. Autric, Excimer laser-induced hydrodynamical effects and surface modifications on silicon carbide 96–98 (1996) 296
Niino, H. and A. Yabe, Chemical surface modification of fluorocarbon polymers by excimer laser processing 96–98 (1996) 550
Niino, H. and A. Yabe, Surface chemical reaction of polymer film with reactive intermediates produced by laser ablation of azido compound 96–98 (1996) 572
Niino, H., see Lippert, T. 96–98 (1996) 601
Nikitin, P.I., see Kabashin, A.V. 96–98 (1996) 139
Norton, D.P., B.C. Chakoumakos, D.H. Lowndes and J.D. Budai, Formation of artificially-layered high-temperature superconductors using pulsed-laser deposition 96–98 (1996) 672
Norton, M.G., W. Jiang, J.T. Dickinson and K.W. Hipps, Pulsed laser ablation and deposition of fluorocarbon polymers 96–98 (1996) 617

Offenberg, D., see Mertin, M. 96–98 (1996) 842
Ohnuma, Y., see Sugioka, K. 96–98 (1996) 347
Ohta, H., see Maruyama, K. 96–98 (1996) 764
Oltra, R., O. Yavaş, F. Cruz, J.P. Boquillon and C. Sartori, Modelling and diagnostic of pulsed laser cleaning of oxidized metallic surfaces 96–98 (1996) 484
Orlando, S., see Mele, A. 96–98 (1996) 102
Ozegowski, M., see Metev, S. 96–98 (1996) 122

Panczer, G., see Garapon, C. 96–98 (1996) 836
Panzner, M., R. Dietsch, Th. Holz, H. Mai and S. Völlmar, Scale-up of pulsed laser deposition (PLD) for 4″-wafer coating 96–98 (1996) 643
Pastoor, E., see Cillessen, J.F.M. 96–98 (1996) 744
Pelli, S., see Afonso, C.N. 96–98 (1996) 760
Perez, A., see Afif, M. 96–98 (1996) 469
Pérez, B., see Gobernado-Mitre, I. 96–98 (1996) 474
Pérez Casero, R., R. Gómez San Román, C. Maréchal, J.P. Enard and J. Perrière, Laser ablation of oxides: study of the oxygen incorporation by ^{18}O isotopic tracing techniques 96–98 (1996) 697
Perrière, J., see Gonzalo, J. 96–98 (1996) 693
Perrière, J., see Pérez Casero, R. 96–98 (1996) 697
Perrin, C., see Barthe, M.F. 96–98 (1996) 359
Perrone, A., see Leggieri, G. 96–98 (1996) 866
Petzoldt, S., J. Reif and E. Matthias, Laser plasma threshold of metals 96–98 (1996) 199
Pfleging, W., D.A. Wesner and E.W. Kreutz, CCl_4-assisted CF_4 etching of silicon in a microwave-assisted LDE (laser dry etching)-process 96–98 (1996) 496
Pireaux, J.J., see Girardeaux, C. 96–98 (1996) 586
Pirš, J., see Kopač, S. 96–98 (1996) 420
Polgár, K., see Alfonso, J.E. 96–98 (1996) 791
Polo, M.C., R. Aguiar, P. Serra, L. Clèries, M. Varela and J. Esteve, Carbon nitride thin films obtained by laser ablation of graphite in a nitrogen plasma 96–98 (1996) 870
Pompe, W., see Gorbunov, A.A. 96–98 (1996) 649
Popovych, D.I., see Kotlyarchuk, B.K. 96–98 (1996) 192
Porte, M., see Guyot, M. 96–98 (1996) 802
Prakash, N.S., see Afif, M. 96–98 (1996) 469
Predtechensky, M.R., O.M. Tukhto, A.N. Smal' and S.A. Vasil'eva, Substrate size effect at off-axis laser deposition of multicomponent films 96–98 (1996) 717
Predtechensky, M.R., see Bulgakov, A.V. 96–98 (1996) 159
Prieto, A.C., see García, C. 96–98 (1996) 370
Prieto, A.C., see Gobernado-Mitre, I. 96–98 (1996) 474
Proyer, S., E. Stangl, M. Borz and D. Bäuerle, Classification of particulates on pulsed-laser deposited Y–Ba–Cu–O films 96–98 (1996) 668
Proyer, S., see Li, S.T. 96–98 (1996) 713
Proyer, S., see Stangl, E. 96–98 (1996) 731
Puretzky, A.A., D.B. Geohegan, G.E. Jellison Jr. and M.M. McGibbon, Comparative diagnostics of ArF- and KrF-laser generated carbon plumes used for amorphous diamond-like carbon film deposition 96–98 (1996) 859
Puretzky, A.A., see Leboeuf, J.N. 96–98 (1996) 14
Puretzky, A.A., see Chen, K.R. 96–98 (1996) 45
Puretzky, A.A., see Geohegan, D.B. 96–98 (1996) 131

Ramos, J., see García, C. 96–98 (1996) 370
Rao, K.V., see Tyunina, M. 96–98 (1996) 831
Ravelosona, D., see Abert, A. 96–98 (1996) 703
Reade, R.P. and R.E. Russo, Ion-assisted pulsed-laser deposition for the fabrication of Y–Ba–Cu–O multilayer structures using oriented intermediate layers of YSZ and CeO_2 96–98 (1996) 726
Rebhan, T., see Geiger, M. 96–98 (1996) 309
Rector, J.H., see Dam, B. 96–98 (1996) 679
Reichling, M., see Gogoll, S. 96–98 (1996) 332
Reif, J., see Petzoldt, S. 96–98 (1996) 199
Reisse, G., S. Weissmantel, B. Keiper and U. Broulik, Deposition of optical coatings by pulsed laser ablation 96–98 (1996) 752
Reitano, R., P. Baeri and N. Marino, Excimer laser induced thermal evaporation and ablation of silicon carbide 96–98 (1996) 302

Reschauer, N., see Li, S.T. 96–98 (1996) 713
Révész, K., see Hopp, B. 96–98 (1996) 611
Righini, G.C., see Afonso, C.N. 96–98 (1996) 760
Rijnders, A.J.H.M., see Blank, D.H.A. 96–98 (1996) 685
Ritzer, A., B. Falkner, S.T. Li and D. Bäuerle, In-situ reflectivity measurements during pulsed-laser deposition of $Bi_2Sr_2CaCu_2O_{8+\delta}$ 96–98 (1996) 721
Ritzer, A., see Li, S.T. 96–98 (1996) 713
Robino, M., see Chergui, A. 96–98 (1996) 874
Roesthuis, F.J.G., see Blank, D.H.A. 96–98 (1996) 685
Rogalla, H., see Blank, D.H.A. 96–98 (1996) 685
Rohr, K., see Granse, G. 96–98 (1996) 97
Romand, M., see Afif, M. 96–98 (1996) 469
Rosenfeld, A. and E.E.B. Campbell, Picosecond UV-laser ablation of Au and Ni films 96–98 (1996) 439
Rougier, P., see Guyot, M. 96–98 (1996) 802
Rowan, C., see Watson, T.A. 96–98 (1996) 532
Rupp, A., see Granse, G. 96–98 (1996) 97
Russo, R.E., X.L. Mao, M. Caetano and M.A. Shannon, Fundamental characteristics of laser–material interactions (ablation) in noble gases at atmospheric pressure using inductively coupled plasma-atomic emission spectroscopy 96–98 (1996) 144
Russo, R.E., see Mao, X. 96–98 (1996) 126
Russo, R.E., see Shannon, M.A. 96–98 (1996) 149
Russo, R.E., see Reade, R.P. 96–98 (1996) 726

Saito, K., see Togashi, H. 96–98 (1996) 267
Salaschenko, N.N., see Gorbunov, A.A. 96–98 (1996) 649
Sameshima, T., Laser beam application to thin film transistors 96–98 (1996) 352
Sánchez, F., see Aguiar, R. 96–98 (1996) 405
Sands, D., see Cranton, W.M. 96–98 (1996) 501
Sartori, C., see Oltra, R. 96–98 (1996) 484
Sassoli, H., see Grangeon, F. 96–98 (1996) 186
Savchuk, V.K., see Kotlyarchuk, B.K. 96–98 (1996) 192
Savitsky, V.G., see Kotlyarchuk, B.K. 96–98 (1996) 192
Schmidt, M.J.J., see Dyer, P.E. 96–98 (1996) 849
Schou, J., see Svendsen, W. 96–98 (1996) 518
Schwegle, W., see Abert, A. 96–98 (1996) 703
Schwentner, N., see Streller, U. 96–98 (1996) 448
Seifert, N., G. Betz and W. Husinsky, Hydrodynamic phenomena during laser irradiation: a finite difference approach 96–98 (1996) 33
Senchenko, V.N., see Ignatiev, M.B. 96–98 (1996) 505
Sentis, M., see Le, H.C. 96–98 (1996) 76
Sentis, M., see Kabashin, A.V. 96–98 (1996) 139
Sentis, M., see Le, H.C. 96–98 (1996) 164
Sentis, M., see Movtchan, I.A. 96–98 (1996) 251
Sepold, G., see Metev, S. 96–98 (1996) 122
Serra, P., L. Clèries and J.L. Morenza, Analysis of the expansion of hydroxyapatite laser ablation plumes 96–98 (1996) 216
Serra, P., see Polo, M.C. 96–98 (1996) 870
Sewing, A., see Gorbunov, A.A. 96–98 (1996) 649
Shafeev, G.A., see Dolgaev, S.I. 96–98 (1996) 491
Shannon, M.A. and R.E. Russo, Monitoring stress power during high-power pulsed laser–material interactions 96–98 (1996) 149
Shannon, M.A., see Mao, X. 96–98 (1996) 126
Shannon, M.A., see Russo, R.E. 96–98 (1996) 144
Sheregii, E., see Gorbach, T.Ya. 96–98 (1996) 881
Shima, H., see Fujii, T. 96–98 (1996) 625
Shin, J.-J., see Dickinson, J.T. 96–98 (1996) 316
Shin, J.J., see Dickinson, J.T. 96–98 (1996) 326
Shuttleworth, S., Optimisation of laser wavelength in the ablation sampling of glass materials 96–98 (1996) 513
Siegbahn, K., see Ding, D. 96–98 (1996) 581
Simakin, A.V., see Dolgaev, S.I. 96–98 (1996) 491
Smal', A.N., see Predtechensky, M.R. 96–98 (1996) 717
Smertenko, P.S., see Gorbach, T.Ya. 96–98 (1996) 881
Smurov, I., see Mazhukin, V.I. 96–98 (1996) 82
Smurov, I., see Mazhukin, V.I. 96–98 (1996) 89
Smurov, I., see Gnedovets, A.G. 96–98 (1996) 272
Smurov, I., see Titov, V. 96–98 (1996) 387
Smurov, I.Yu., see Ignatiev, M.B. 96–98 (1996) 505
Spinelli, N., see Amoruso, S. 96–98 (1996) 175
Sreenivas, K., see Tyunina, M. 96–98 (1996) 831
Stamm, H., see Alunovic, M. 96–98 (1996) 222
Stangl, E., S. Proyer, B. Hellebrand and D. Bäuerle, Synthesis of RE–Ba–Sr–Cu–O by pulsed-laser deposition 96–98 (1996) 731
Stangl, E., see Proyer, S. 96–98 (1996) 668
Stangl, E., see Li, S.T. 96–98 (1996) 713
Stauter, C., J. Fontaine and Th. Engel, Real-time determination of the amount of removed material during short pulses laser micromachining 96–98 (1996) 522
Stehle, J.L., see Boher, P. 96–98 (1996) 376
Stehle, M., see Boher, P. 96–98 (1996) 376
Stenzel, E., see Gogoll, S. 96–98 (1996) 332
Stephenson, J.D., White synchrotron X-radiation-section topography of high energy density ns-pulsed (Nd:YAG) ablation damage in Si(100) wafers 96–98 (1996) 528
Streller, U., B. Li, A. Krabbe and N. Schwentner, Photon-induced dry etching of Si(100) in the VUV 96–98 (1996) 448
Stuke, M., see Götz, T. 96–98 (1996) 280
Sugihara, T., see Kuba, K. 96–98 (1996) 659
Sugioka, K., S. Wada, Y. Ohnuma, A. Nakamura, H. Tashiro and K. Toyoda, Multiwavelength irradiation effect in fused quartz ablation using vacuum-ultraviolet Raman laser 96–98 (1996) 347
Sugiyama, S., see Deno, H. 96–98 (1996) 563
Sundqvist, B.U.R., see Ehring, H. 96–98 (1996) 577
Svanberg, S., see Grätz, M. 96–98 (1996) 443
Svechnikov, S.V., see Gorbach, T.Ya. 96–98 (1996) 881
Svendsen, W., J. Schou, B. Thestrup and O. Ellegaard, Ablation from metals induced by visible and UV laser irradiation 96–98 (1996) 518

Swensson, P., see Ding, D. 96–98 (1996) 581
Szörényi, T., L.D. Laude, I. Bertóti, Zs. Geretovszky and Z. Kántor, Low-fluence excimer laser irradiation-induced defect formation in indium–tin oxide films 96–98 (1996) 363

Tait, J.P., see Dyer, P.E. 96–98 (1996) 596
Tapfer, L., see Berling, D. 96–98 (1996) 739
Tashiro, H., see Sugioka, K. 96–98 (1996) 347
Teghil, R., see Mele, A. 96–98 (1996) 102
Thestrup, B., see Svendsen, W. 96–98 (1996) 518
Thomas, C.B., see Cranton, W.M. 96–98 (1996) 501
Thomy, A., see Dauscher, A. 96–98 (1996) 410
Thorns, A., see Goerke, F. 96–98 (1996) 708
Tillman, C., see Grätz, M. 96–98 (1996) 443
Titov, V., I. Smurov and M. Ignatiev, Erosion plume dynamics during pulsed laser alloying 96–98 (1996) 387
Togashi, H., K. Saito, Y. Koga, H. Yamawaki, K. Aoki, M. Mukaida and T. Kameyama, Formation of large carbon cluster ions at graphite (HOPG) surfaces by laser irradiation 96–98 (1996) 267
Tomas, C., see Afif, M. 96–98 (1996) 469
Toshima, S., see Inoue, N. 96–98 (1996) 656
Tosin, P., W. Lüthy and H.P. Weber, Liquid carbon observed with reflection measurements on CVD-diamond under UV pulsed-laser irradiation 96–98 (1996) 384
Toyoda, K., see Sugioka, K. 96–98 (1996) 347
Träger, F., see Götz, T. 96–98 (1996) 280
Tsai, C.H., see Chung, B.C. 96–98 (1996) 233
Tsai, C.H., see Huang, C.S. 96–98 (1996) 735
Tseng, T.Y., see Chung, B.C. 96–98 (1996) 233
Tseng, T.Y., see Huang, C.S. 96–98 (1996) 735
Tukhto, O.M., see Predtechensky, M.R. 96–98 (1996) 717
Turcotte, G., see Lecours, A. 96–98 (1996) 341
Tyrrell, G.C., L.G. Coccia, T.H. York and I.W. Boyd, Energy-dispersive mass spectrometry of high energy ions generated during KrF excimer and frequency-doubled Nd:YAG laser ablation of metals 96–98 (1996) 227
Tyrrell, G.C., T.H. York, L.G. Coccia and I.W. Boyd, Kinetic energy distributions of ions ejected during laser ablation of lead zirconate titanate and their correlation to deposition of ferroelectric thin films 96–98 (1996) 769
Tyrrell, G.C., see Coccia, L.G. 96–98 (1996) 795
Tyunina, M., K. Sreenivas, C. Bjormander, J. Wittborn and K.V. Rao, An experimental study and modeling of the thickness distribution in pulsed laser deposited ferroelectric thin films 96–98 (1996) 831
Tzolov, M., see Dimova-Malinovska, D. 96–98 (1996) 457

Varela, M., see Aguiar, R. 96–98 (1996) 405
Varela, M., see Polo, M.C. 96–98 (1996) 870
Vasil'eva, S.A., see Predtechensky, M.R. 96–98 (1996) 717
Velotta, R., see Amoruso, S. 96–98 (1996) 175
Verardi, P., M. Dinescu and A. Andrei, Characterization of ZnO thin films deposited by laser ablation in reactive atmosphere 96–98 (1996) 827
Vinkó, J., see Hopp, B. 96–98 (1996) 611
Vivet, L., B. Dubreuil, T. Gibert-Legrand and M.F. Barthe, Soft laser sputtering of the GaAlAs (100) surface 96–98 (1996) 238
Vivet, L., see Barthe, M.F. 96–98 (1996) 359
Viville, P., S. Beauvois, G. Lambin, R. Lazzaroni, J.L. Brédas, K. Kolev and L. Laude, Excimer laser-induced surface modifications of biocompatible polymer blends 96–98 (1996) 558
Völlmar, S., see Granse, G. 96–98 (1996) 97
Völlmar, S., see Panzner, M. 96–98 (1996) 643
Völlmar, S., see Gorbunov, A.A. 96–98 (1996) 649
Vuillon, J., see Le, H.C. 96–98 (1996) 76
Vyacheslavov, L.N., see Fuso, F. 96–98 (1996) 181

Wada, S., see Sugioka, K. 96–98 (1996) 347
Wagner, F.X., see Cranton, W.M. 96–98 (1996) 501
Wagner, J.W., see Diaci, J. 96–98 (1996) 154
Waller, D., see Coccia, L.G. 96–98 (1996) 795
Waser, R., see Grosse-Holz, K.-O. 96–98 (1996) 784
Watson, T.A. and C. Rowan, Industrial excimer laser beam properties 96–98 (1996) 532
Weaver, I. and C.L.S. Lewis, Aspects of particulate production from metals exposed to pulsed laser radiation 96–98 (1996) 663
Weber, H.P., see Tosin, P. 96–98 (1996) 384
Weissmantel, S., see Reisse, G. 96–98 (1996) 752
Welsch, E., K. Ettrich, H. Blaschke and N. Kaiser, Excimer laser interaction with dielectric thin films 96–98 (1996) 393
Wesner, D.A., M. Mertin, F. Lupp and E.W. Kreutz, Cleaning of copper traces on circuit boards with excimer laser radiation 96–98 (1996) 479
Wesner, D.A., see Pfleging, W. 96–98 (1996) 496
Wesner, D.A., see Mertin, M. 96–98 (1996) 842
Wistus, E., see Ding, D. 96–98 (1996) 581
Wisz, G., see Gorbach, T.Ya. 96–98 (1996) 881
Witke, Th., see Lenk, A. 96–98 (1996) 195
Wittborn, J., see Tyunina, M. 96–98 (1996) 831
Wolf, R.M., see Cillessen, J.F.M. 96–98 (1996) 744
Wolff-Rottke, B., see Mann, K. 96–98 (1996) 463
Wood, R.F., see Leboeuf, J.N. 96–98 (1996) 14
Wood, R.F., see Chen, K.R. 96–98 (1996) 45

Yabe, A., see Niino, H. 96–98 (1996) 550
Yabe, A., see Niino, H. 96–98 (1996) 572
Yabe, A., see Lippert, T. 96–98 (1996) 601
Yamawaki, H., see Togashi, H. 96–98 (1996) 267

Yavaş, O., see Oltra, R. 96–98 (1996) 484
Yelon, A., see Lecours, A. 96–98 (1996) 341
Yelon, A., see Izquierdo, R. 96–98 (1996) 855
York, T.H., see Tyrrell, G.C. 96–98 (1996) 227
York, T.H., see Tyrrell, G.C. 96–98 (1996) 769
Yoshida, M., see Deno, H. 96–98 (1996) 563

Zabrodin, I.G., see Gorbunov, A.A. 96–98 (1996) 649
Zaldo, C., see Alfonso, J.E. 96–98 (1996) 791
Zaldo, C., see Martín, M.J. 96–98 (1996) 823
Zeitoun, D., see Le, H.C. 96–98 (1996) 76
Zhang, J.-Y., H. Esrom and I.W. Boyd, Decomposition mechanisms of thin palladium acetate film with excimer UV radiation 96–98 (1996) 399
Zhu, S.N., see Liu, J.M. 96–98 (1996) 819
Zhu, Y.Y., see Liu, J.M. 96–98 (1996) 819
Ziemann, P., see Abert, A. 96–98 (1996) 703
Zimmer, K., D. Hirsch and F. Bigl, Excimer laser machining for the fabrication of analogous microstructures 96–98 (1996) 425

ELSEVIER

Applied Surface Science 96–98 (1996) 902–924

applied surface science

Subject index

Ablation

Microscopic and mesoscopic aspects of laser-induced desorption and ablation, R.F. Haglund, Jr. 96–98 (1996) 1

Modeling of dynamical processes in laser ablation, J.N. Leboeuf, K.R. Chen, J.M. Donato, D.B. Geohegan, C.L. Liu, A.A. Puretzky and R.F. Wood 96–98 (1996) 14

An analytical model for three-dimensional laser plume expansion into vacuum in hydrodynamic regime, S.I. Anisimov, B.S. Luk'yanchuk and A. Luches 96–98 (1996) 24

Laser–solid interaction and dynamics of laser-ablated materials, K.R. Chen, J.N. Leboeuf, R.F. Wood, D.B. Geohegan, J.M. Donato, C.L. Liu and A.A. Puretzky 96–98 (1996) 45

Analytical description of the film thickness distribution obtained by the pulsed laser ablation of a monoatomic target: application to silicon and germanium, F. Antoni, C. Fuchs and E. Fogarassy 96–98 (1996) 50

An analytical model for the laser ablation of materials, A.D. Boardman, B. Cresswell and J. Anderson 96–98 (1996) 55

Calculations and experiments of material removal and kinetic energy during pulsed laser ablation of metals, S. Fähler and H.-U. Krebs 96–98 (1996) 61

Measurement and calculation of the Fe_2O_3 ablation depth, A. Lisfi, M. Guyot, R. Krishnan and V. Cagan 96–98 (1996) 66

Calculation and measurement of the ultrasonic signals generated by ablating material with a Q-switched pulse laser, A. Hoffmann and W. Arnold 96–98 (1996) 71

2D modeling of laser-induced plume expansion near the plasma ignition threshold, H.C. Le, J. Vuillon, D. Zeitoun, W. Marine, M. Sentis and R.W. Dreyfus 96–98 (1996) 76

Spatial distribution of laser-ablated material by probing a plasma plume in three dimensions, A. Mele, A. Giardini Guidoni, R. Kelly, A. Miotello, S. Orlando and R. Teghil 96–98 (1996) 102

Electrostatic probe and optical spectroscopy studies of low temperature laser produced plasmas, J.M. Hendron, R.A. Al-Wazzan, C. Mahony, T. Morrow and W.G. Graham 96–98 (1996) 112

Study of the expansion of the laser ablation plume above a boron nitride target, B. Angleraud, C. Girault, C. Champeaux, F. Garrelie, C. Germain and A. Catherinot 96–98 (1996) 117

Preferential vaporization and plasma shielding during nano-second laser ablation, X. Mao, W.-T. Chan, M. Caetano, M.A. Shannon and R.E. Russo 96–98 (1996) 126

Laser ablation plume thermalization dynamics in background gases: combined imaging, optical absorption and emission spectroscopy, and ion probe measurements, D.B. Geohegan and A.A. Puretzky 96–98 (1996) 131

Fundamental characteristics of laser–material interactions (ablation) in noble gases at atmospheric pressure using inductively coupled plasma-atomic emission spectroscopy, R.E. Russo, X.L. Mao, M. Caetano and M.A. Shannon 96–98 (1996) 144

Simultaneous monitoring of ablative shocks in air by high-speed cineholography and multiple-pass beam deflection probe, J. Diaci, D. Hurley, J.W. Wagner and J. Možina 96–98 (1996) 154

Transport of neutral atoms, monoxides and clusters in the plume produced by laser ablation of $YBa_2Cu_3O_{7-x}$ in oxygen environment, A.V. Bulgakov, M.R. Predtechensky and A.P. Mayorov 96–98 (1996) 159

Temperature measurements during laser ablation of Si into He, Ar and O_2, H.C. Le, R.W. Dreyfus, W. Marine, M. Sentis and I.A. Movtchan 96–98 (1996) 164

Spatially and temporally resolved emission intensities and number densities in low

temperature laser-induced plasmas in vacuum and in ambient gases, R.A. Al-Wazzan, J.M. Hendron and T. Morrow 96–98 (1996) 170
Laser produced plasmas in high fluence ablation of metallic surfaces probed by time-of-flight mass spectrometry, S. Amoruso, A. Amodeo, V. Berardi, R. Bruzzese, N. Spinelli and R. Velotta 96–98 (1996) 175
Optical diagnostics of the laser–target and laser–plume interaction in pulsed laser ablation, F. Fuso, L.N. Vyacheslavov, G. Lorenzi, M. Allegrini and E. Arimondo 96–98 (1996) 181
Time-of-flight characterization of laser ablation plume from $NbTe_2$ target in He atmosphere, F. Grangeon, H. Sassoli, W. Marine and M. Autric 96–98 (1996) 186
Laser plasma threshold of metals, S. Petzoldt, J. Reif and E. Matthias 96–98 (1996) 199
Comments on explosive mechanisms of laser sputtering, R. Kelly and A. Miotello 96–98 (1996) 205
Optical and particle properties of PLD vapour/plasmas of ceramics, M. Alunovic, H. Stamm, M. Aden and E.W. Kreutz 96–98 (1996) 222
Energy-dispersive mass spectrometry of high energy ions generated during KrF excimer and frequency-doubled Nd:YAG laser ablation of metals, G.C. Tyrrell, L.G. Coccia, T.H. York and I.W. Boyd 96–98 (1996) 227
Soft laser sputtering of the GaAlAs (100) surface, L. Vivet, B. Dubreuil, T. Gibert-Legrand and M.F. Barthe 96–98 (1996) 238
Dynamics of silicon plume generated by laser ablation and its chemical reaction, T. Makimura and K. Murakami 96–98 (1996) 242
Optical spectroscopy of emission from Si–SiO_x nanoclusters formed by laser ablation, I.A. Movtchan, W. Marine, R.W. Dreyfus, H.C. Le, M. Sentis and M. Autric 96–98 (1996) 251
Magnetic field enhanced growth of carbon cluster ions in the laser ablation plume of graphite, F. Kokai, Y. Koga and R.B. Heimann 96–98 (1996) 261
Particles synthesis in erosive laser plasma in a high pressure atmosphere, A.G. Gnedovets, E.B. Kul'batskii, I. Smurov and G. Flamant 96–98 (1996) 272
Laser ablation of metals: the transition from non-thermal processes to thermal evaporation, T. Götz, M. Bergt, W. Hoheisel, F. Träger and M. Stuke 96–98 (1996) 280
Excimer laser induced thermal evaporation and ablation of silicon carbide, R. Reitano, P. Baeri and N. Marino 96–98 (1996) 302
Increase of efficiency for the XeCl excimer laser ablation of ceramics, M. Geiger, W. Becker, T. Rebhan, J. Hutfless and N. Lutz 96–98 (1996) 309
Laser ablation of sodium nitrate: NO desorption following excitation of the π–π^* band of the nitrate anion, W.P. Hess, K.A.H. German, R.A. Bradley and M.I. McCarthy 96–98 (1996) 321
Laser patterning of thin-film electrochemical gas sensors, A. Lecours, M. Caron, P. Ciureanu, G. Turcotte, D. Ivanov, A. Yelon and J.F. Currie 96–98 (1996) 341
Multiwavelength irradiation effect in fused quartz ablation using vacuum-ultraviolet Raman laser, K. Sugioka, S. Wada, Y. Ohnuma, A. Nakamura, H. Tashiro and K. Toyoda 96–98 (1996) 347
Micro-Raman study of UV laser ablation of GaAs and Si substrates, C. García, J. Ramos, A.C. Prieto, J. Jiménez, C. Geertsen, J.L. Lacour and P. Mauchien 96–98 (1996) 370
Erosion plume dynamics during pulsed laser alloying, V. Titov, I. Smurov and M. Ignatiev 96–98 (1996) 387
Excimer laser ablation for micro-machining: geometric effects, P.E. Dyer, D.M. Karnakis, P.H. Key and P. Monk 96–98 (1996) 415
Optodynamics of laser ablation of graduation lines in chromium thin film on glass, S. Kopač, J. Pirš and J. Možina 96–98 (1996) 420
Picosecond UV-laser ablation of Au and Ni films, A. Rosenfeld and E.E.B. Campbell 96–98 (1996) 439
XeCl laser ablation of thin film ZnS, W.M. Cranton, P.H. Key, D. Sands, C.B. Thomas and F.X. Wagner 96–98 (1996) 501
Optimisation of laser wavelength in the ablation sampling of glass materials, S. Shuttleworth 96–98 (1996) 513
Ablation from metals induced by visible and UV laser irradiation, W. Svendsen, J. Schou, B. Thestrup and O. Ellegaard 96–98 (1996) 518
Real-time determination of the amount of removed material during short pulses laser micromachining, C. Stauter, J. Fontaine and Th. Engel 96–98 (1996) 522
Excimer laser ablation of polymers and glasses for grating fabrication, P.E. Dyer, R.J. Farley, R. Giedl and D.M. Karnakis 96–98 (1996) 537
VUV ablation of polymers by emission from gas-puff Z-pinch plasmas, H. Deno, S. Sugiyama, Y. Kakudate, M. Yoshida and S. Fujiwara 96–98 (1996) 563
Surface chemical reaction of polymer film with reactive intermediates produced by

laser ablation of azido compound, H. Niino and A. Yabe 96–98 (1996) 572
Excimer laser ablation of low and high absorption index polymers, P.E. Dyer, D.M. Karnakis, P.H. Key and J.P. Tait 96–98 (1996) 596
High sensitivity quadrupole mass spectrometry of neutrals sputtered by UV-laser ablation of polymers, S. Lazare, W. Guan and D. Drilhole 96–98 (1996) 605
Formation of the surface structure of polyethylene-terephtalate (PET) due to ArF excimer laser ablation, B. Hopp, M. Csete, K. Révész, J. Vinkó and Zs. Bor 96–98 (1996) 611
Pulsed laser ablation and deposition of fluorocarbon polymers, M.G. Norton, W. Jiang, J.T. Dickinson and K.W. Hipps 96–98 (1996) 617
Deposition of fluoropolymer thin films containing semiconductor microcrystallites by VUV laser ablation, T. Fujii, S. Inoue and F. Kannari 96–98 (1996) 621
Thin film growth by the pulsed laser assisted deposition technique, C. Belouet 96–98 (1996) 630
Ultrathin film deposition by pulsed laser ablation using crossed beams, A.A. Gorbunov, W. Pompe, A. Sewing, S.V. Gaponov, A.D. Akhsakhalyan, I.G. Zabrodin, I.A. Kas'kov, E.B. Klyenkov, A.P. Morozov, N.N. Salaschenko, R. Dietsch, H. Mai and S. Völlmar 96–98 (1996) 649
Selection of kinetic energy of laser ablated particles, K. Kuba and T. Sugihara 96–98 (1996) 659
Aspects of particulate production from metals exposed to pulsed laser radiation, I. Weaver and C.L.S. Lewis 96–98 (1996) 663
Formation of artificially-layered high-temperature superconductors using pulsed-laser deposition, D.P. Norton, B.C. Chakoumakos, D.H. Lowndes and J.D. Budai 96–98 (1996) 672
The importance of gas scattering processes on the stoichiometry deviations of laser deposited films, J. Gonzalo, C.N. Afonso, J. Perrière and R. Gómez San Roman 96–98 (1996) 693
Laser ablation of oxides: study of the oxygen incorporation by ^{18}O isotopic tracing techniques, R. Pérez Casero, R. Gómez San Román, C. Maréchal, J.P. Enard and J. Perrière 96–98 (1996) 697
Substrate size effect at off-axis laser deposition of multicomponent films, M.R. Predtechensky, O.M. Tukhto, A.N. Smal' and S.A. Vasil'eva 96–98 (1996) 717
Deposition of optical coatings by pulsed laser ablation, G. Reisse, S. Weissmantel, B. Keiper and U. Broulik 96–98 (1996) 752
Preparation of SiO_xN_y films by reactive KrF laser ablation, K. Maruyama, Y. Aoki, M. Matsumoto, Y. Hiroshima and H. Ohta 96–98 (1996) 764
Kinetic energy distributions of ions ejected during laser ablation of lead zirconate titanate and their correlation to deposition of ferroelectric thin films, G.C. Tyrrell, T.H. York, L.G. Coccia and I.W. Boyd 96–98 (1996) 769
Excimer laser ablating preparation of $Ba_2NaNb_5O_{15}$ thin films on $KTiOPO_4$ substrate and its guide wave property, J.M. Liu, Z.G. Liu, S.N. Zhu, Y.Y. Zhu and N.B. Ming 96–98 (1996) 819
$Pb_{1-x}Ca_xTiO_3$ thin films prepared by laser ablation of ceramic targets, M.J. Martín, C. Zaldo and J. Mendiola 96–98 (1996) 823
Excimer laser ablation and film deposition of Ti:sapphire, P.E. Dyer, S.R. Jackson, P.H. Key, W.J. Metheringham and M.J.J. Schmidt 96–98 (1996) 849
Laser reactive ablation deposition of silicon carbide films, G. Leggieri, A. Luches, M. Martino, A. Perrone, R. Alexandrescu, A. Barborica, E. Gyorgy, I.N. Mihailescu, G. Majni and P. Mengucci 96–98 (1996) 866
Carbon nitride thin films obtained by laser ablation of graphite in a nitrogen plasma, M.C. Polo, R. Aguiar, P. Serra, L. Clèries, M. Varela and J. Esteve 96–98 (1996) 870

Alkali metals

Laser-induced emission of neutral atoms and molecules from electron-irradiated $NaNO_3$, J.T. Dickinson, J.J. Shin and S.C. Langford 96–98 (1996) 326
Pulsed laser deposition of nasicon thin films, R. Izquierdo, F. Hanus, Th. Lang, D. Ivanov, M. Meunier, L. Laude, J.F. Currie and A. Yelon 96–98 (1996) 855

Alloys

Erosion plume dynamics during pulsed laser alloying, V. Titov, I. Smurov and M. Ignatiev 96–98 (1996) 387

Aluminium

Soft laser sputtering of the GaAlAs (100) surface, L. Vivet, B. Dubreuil, T. Gibert-Legrand and M.F. Barthe 96–98 (1996) 238
Aspects of particulate production from metals exposed to pulsed laser radiation, I. Weaver and C.L.S. Lewis 96–98 (1996) 663

Aluminium oxide

Fast etching of sapphire by a visible range quasi-cw laser radiation, S.I. Dolgaev, A.A. Lyalin, A.V. Simakin and G.A. Shafeev 96–98 (1996) 491
Excimer laser ablation and film deposition of Ti:sapphire, P.E. Dyer, S.R. Jackson, P.H. Key, W.J. Metheringham and M.J.J. Schmidt 96–98 (1996) 849

Ammonia

Laser induced nitridation of Ga on GaAs surfaces, M.F. Barthe, C. Perrin, L. Vivet, B. Dubreuil and T. Gibert 96–98 (1996) 359

Annealing

Single shot excimer laser annealing of amorphous silicon for AMLCD, P. Boher, J.L. Stehle, M. Stehle and B. Godard 96–98 (1996) 376

Arsenic

Soft laser sputtering of the GaAlAs (100) surface, L. Vivet, B. Dubreuil, T. Gibert-Legrand and M.F. Barthe 96–98 (1996) 238

Atomic force microscopy

Excimer laser machining for the fabrication of analogous microstructures, K. Zimmer, D. Hirsch and F. Bigl 96–98 (1996) 425
Picosecond UV-laser ablation of Au and Ni films, A. Rosenfeld and E.E.B. Campbell 96–98 (1996) 439
Formation of the surface structure of polyethylene-terephtalate (PET) due to ArF excimer laser ablation, B. Hopp, M. Csete, K. Révész, J. Vinkó and Zs. Bor 96–98 (1996) 611
Improved properties of Pulsed Laser Deposited YBaCuO on $NdGaO_3$ using CeO_2 template layers, D.H.A. Blank, A.J.H.M. Rijnders, F.J.G. Roesthuis, G. den Ouden and H. Rogalla 96–98 (1996) 685
Mirror-smooth $YBa_2Cu_3O_{7-x}$ superconducting films deposited by plasma-enhanced pulsed laser deposition technique, C.S. Huang, T.Y. Tseng, B.C. Chung, C.H. Tsai, H.F. Cheng and I.N. Lin 96–98 (1996) 735
Ferrimagnetic thin films prepared by pulsed laser deposition, M. Guyot, A. Lisfi, R. Krishnan, M. Porte, P. Rougier and V. Cagan 96–98 (1996) 802
Structural and optical characteristics of pulsed laser deposited ZnSe epilayers, A. Chergui, J.L. Deiss, J.B. Grun, J.L. Loison, M. Robino and R. Beserman 96–98 (1996) 874

Auger electron spectroscopy

Excimer laser-induced hydrodynamical effects and surface modifications on silicon carbide, G. Nicolas and M. Autric 96–98 (1996) 296
Laser induced nitridation of Ga on GaAs surfaces, M.F. Barthe, C. Perrin, L. Vivet, B. Dubreuil and T. Gibert 96–98 (1996) 359
Modelling and diagnostic of pulsed laser cleaning of oxidized metallic surfaces, R. Oltra, O. Yavaş, F. Cruz, J.P. Boquillon and C. Sartori 96–98 (1996) 484
Pulsed laser deposition of high quality ITO thin films, F. Hanus, A. Jadin and L.D. Laude 96–98 (1996) 807

Boron nitride

Study of the expansion of the laser ablation plume above a boron nitride target, B. Angleraud, C. Girault, C. Champeaux, F. Garrelie, C. Germain and A. Catherinot 96–98 (1996) 117

Cadmium

Investigation of vaporization and condensation processes of thin layers of CdHgTe from laser erosion plasma in Hg atmosphere, B.K. Kotlyarchuk, D.I. Popovych, V.K. Savchuk and V.G. Savitsky 96–98 (1996) 192
Deposition of HgCdTe epitaxial layers on anisotropically etched silicon surfaces by laser evaporation, T.Ya. Gorbach, M. Kuźma, E. Sheregii, P.S. Smertenko, S.V. Svechnikov and G. Wisz 96–98 (1996) 881

Calcium

$Pb_{1-x}Ca_xTiO_3$ thin films prepared by laser ablation of ceramic targets, M.J. Martín, C. Zaldo and J. Mendiola 96–98 (1996) 823

Calcium fluoride

Laser damage of $CaF_2(111)$ surfaces at 248 nm, S. Gogoll, E. Stenzel, M. Reichling, H. Johansen and E. Matthias 96–98 (1996) 332

Carbon

Magnetic field enhanced growth of carbon cluster ions in the laser ablation plume of graphite, F. Kokai, Y. Koga and R.B. Heimann 96–98 (1996) 261

Formation of large carbon cluster ions at graphite (HOPG) surfaces by laser irradiation, H. Togashi, K. Saito, Y. Koga, H. Yamawaki, K. Aoki, M. Mukaida and T. Kameyama 96–98 (1996) 267

Carbon nitride thin films obtained by laser ablation of graphite in a nitrogen plasma, M.C. Polo, R. Aguiar, P. Serra, L. Clèries, M. Varela and J. Esteve 96–98 (1996) 870

Ceramics

Optical diagnostics of the laser–target and laser–plume interaction in pulsed laser ablation, F. Fuso, L.N. Vyacheslavov, G. Lorenzi, M. Allegrini and E. Arimondo 96–98 (1996) 181

Optical and particle properties of PLD vapour/plasmas of ceramics, M. Alunovic, H. Stamm, M. Aden and E.W. Kreutz 96–98 (1996) 222

Increase of efficiency for the XeCl excimer laser ablation of ceramics, M. Geiger, W. Becker, T. Rebhan, J. Hutfless and N. Lutz 96–98 (1996) 309

Surface temperature measurements during pulsed laser action on metallic and ceramic materials, M.B. Ignatiev, I.Yu. Smurov, G. Flamant and V.N. Senchenko 96–98 (1996) 505

$Pb_{1-x}Ca_xTiO_3$ thin films prepared by laser ablation of ceramic targets, M.J. Martín, C. Zaldo and J. Mendiola 96–98 (1996) 823

Pulsed laser deposition of electroceramic thin films, M. Mertin, D. Offenberg, C.W. An, D.A. Wesner and E.W. Kreutz 96–98 (1996) 842

Chemical vapour deposition

Liquid carbon observed with reflection measurements on CVD-diamond under UV pulsed-laser irradiation, P. Tosin, W. Lüthy and H.P. Weber 96–98 (1996) 384

Decomposition mechanisms of thin palladium acetate film with excimer UV radiation, J.-Y. Zhang, H. Esrom and I.W. Boyd 96–98 (1996) 399

Chromium

Optodynamics of laser ablation of graduation lines in chromium thin film on glass, S. Kopač, J. Pirš and J. Možina 96–98 (1996) 420

Computer simulations

An analytical model for the laser ablation of materials, A.D. Boardman, B. Cresswell and J. Anderson 96–98 (1996) 55

Copper

Preferential vaporization and plasma shielding during nano-second laser ablation, X. Mao, W.-T. Chan, M. Caetano, M.A. Shannon and R.E. Russo 96–98 (1996) 126

Electromagnetic diagnostics during pulsed laser deposition, A.V. Kabashin, W. Marine, P.I. Nikitin and M. Sentis 96–98 (1996) 139

The role of gas-phase in the laser etching of Cu by CCl_4, D. Débarre, A. Aliouchouche, J. Boulmer, B. Bourguignon and J.P. Budin 96–98 (1996) 453

Aspects of particulate production from metals exposed to pulsed laser radiation, I. Weaver and C.L.S. Lewis 96–98 (1996) 663

Depth profiling

Excimer laser-induced hydrodynamical effects and surface modifications on silicon carbide, G. Nicolas and M. Autric 96–98 (1996) 296

Diamond

Liquid carbon observed with reflection measurements on CVD-diamond under UV pulsed-laser irradiation, P. Tosin, W. Lüthy and H.P. Weber 96–98 (1996) 384

Comparative diagnostics of ArF- and KrF-laser generated carbon plumes used for amorphous diamond-like carbon film deposition, A.A. Puretzky, D.B. Geohegan, G.E. Jellison Jr. and M.M. McGibbon 96–98 (1996) 859

Electrical properties

Electrical and optical characteristics of organic thin films fabricated by laser ablation, T. Fujii, H. Shima, N. Matsumoto and F. Kannari 96–98 (1996) 625

Giant laser-induced voltages at room temperature in Pr doped Y–Ba–Cu–O thin films, H.-U. Habermeier, N. Jisrawi and G. Jäger-Waldau 96–98 (1996) 689

Electrical characterization of semiconducting La doped $SrTiO_3$ thin films prepared by pulsed laser deposition, K.-O. Grosse-Holz, J.F.M. Cillessen and R. Waser 96–98 (1996) 784

Pulsed laser deposition of nasicon thin films, R. Izquierdo, F. Hanus, Th. Lang, D. Ivanov, M. Meunier, L. Laude, J.F. Currie and A. Yelon 96–98 (1996) 855

Electron microscopy

Soft laser sputtering of the GaAlAs (100) surface, L. Vivet, B. Dubreuil, T. Gibert-Legrand and M.F. Barthe 96–98 (1996) 238
Formation of large carbon cluster ions at graphite (HOPG) surfaces by laser irradiation, H. Togashi, K. Saito, Y. Koga, H. Yamawaki, K. Aoki, M. Mukaida and T. Kameyama 96–98 (1996) 267
Particles synthesis in erosive laser plasma in a high pressure atmosphere, A.G. Gnedovets, E.B. Kul'batskii, I. Smurov and G. Flamant 96–98 (1996) 272
Laser induced periodic surface structures on iron, A. Dauscher, V. Feregotto, P. Cordier and A. Thomy 96–98 (1996) 410
Laser cleaning in art restoration, I. Gobernado-Mitre, J. Medina, B. Calvo, A.C. Prieto, L.A. Leal, B. Pérez, F. Marcos and A.M. de Frutos 96–98 (1996) 474
Modelling and diagnostic of pulsed laser cleaning of oxidized metallic surfaces, R. Oltra, O. Yavaş, F. Cruz, J.P. Boquillon and C. Sartori 96–98 (1996) 484
Fast etching of sapphire by a visible range quasi-cw laser radiation, S.I. Dolgaev, A.A. Lyalin, A.V. Simakin and G.A. Shafeev 96–98 (1996) 491
Selection of kinetic energy of laser ablated particles, K. Kuba and T. Sugihara 96–98 (1996) 659
Classification of particulates on pulsed-laser deposited Y–Ba–Cu–O films, S. Proyer, E. Stangl, M. Borz and D. Bäuerle 96–98 (1996) 668
Stoichiometric transfer of complex oxides by pulsed laser deposition, B. Dam, J.H. Rector, J. Johansson, S. Kars and R. Griessen 96–98 (1996) 679
Improved properties of Pulsed Laser Deposited YBaCuO on $NdGaO_3$ using CeO_2 template layers, D.H.A. Blank, A.J.H.M. Rijnders, F.J.G. Roesthuis, G. den Ouden and H. Rogalla 96–98 (1996) 685
Laser deposition of $YBa_2Cu_3O_7$ films on MgO(100) at 100 mm target–substrate distance and oxygen pressures below 0.1 mbar, F. Goerke, A. Thorns and U. Merkt 96–98 (1996) 708
Anisotropic resistivity in pulsed-laser deposited $Bi_2Sr_2CaCu_2O_{8+\delta}$ films, S.T. Li, A. Ritzer, S. Proyer, E. Stangl, D. Bäuerle and N. Reschauer 96–98 (1996) 713
Preparation of SiO_xN_y films by reactive KrF laser ablation, K. Maruyama, Y. Aoki, M. Matsumoto, Y. Hiroshima and H. Ohta 96–98 (1996) 764
Excimer laser ablating preparation of $Ba_2NaNb_5O_{15}$ thin films on $KTiOPO_4$ substrate and its guide wave property, J.M. Liu, Z.G. Liu, S.N. Zhu, Y.Y. Zhu and N.B. Ming 96–98 (1996) 819
Characterization of ZnO thin films deposited by laser ablation in reactive atmosphere, P. Verardi, M. Dinescu and A. Andrei 96–98 (1996) 827
Deposition of HgCdTe epitaxial layers on anisotropically etched silicon surfaces by laser evaporation, T.Ya. Gorbach, M. Kuźma, E. Sheregii, P.S. Smertenko, S.V. Svechnikov and G. Wisz 96–98 (1996) 881

Ellipsometry

Single shot excimer laser annealing of amorphous silicon for AMLCD, P. Boher, J.L. Stehle, M. Stehle and B. Godard 96–98 (1996) 376
Cleaning of copper traces on circuit boards with excimer laser radiation, D.A. Wesner, M. Mertin, F. Lupp and E.W. Kreutz 96–98 (1996) 479
Scale-up of pulsed laser deposition (PLD) for 4″-wafer coating, M. Panzner, R. Dietsch, Th. Holz, H. Mai and S. Völlmar 96–98 (1996) 643
Comparative diagnostics of ArF- and KrF-laser generated carbon plumes used for amorphous diamond-like carbon film deposition, A.A. Puretzky, D.B. Geohegan, G.E. Jellison Jr. and M.M. McGibbon 96–98 (1996) 859

Epitaxy

Formation of artificially-layered high-temperature superconductors using pulsed-laser deposition, D.P. Norton, B.C. Chakoumakos, D.H. Lowndes and J.D. Budai 96–98 (1996) 672
Reactive laser deposition of high quality YBaCuO and ErBaCuO films, D. Berling, A. Del Vecchio, S. Acquaviva, D. Bolmont, G. Leggieri, B. Loegel, M. Luisa De Giorgi, A. Luches, A. Mehdaoui and L. Tapfer 96–98 (1996) 739
Epitaxial ferroelectric PZT and BST thin films by pulsed UV laser deposition, C. Champeaux, P. Marchet and A. Catherinot 96–98 (1996) 775

Structural and optical characteristics of pulsed laser deposited ZnSe epilayers, A. Chergui, J.L. Deiss, J.B. Grun, J.L. Loison, M. Robino and R. Beserman 96–98 (1996) 874
Deposition of HgCdTe epitaxial layers on anisotropically etched silicon surfaces by laser evaporation, T.Ya. Gorbach, M. Kuźma, E. Sheregii, P.S. Smertenko, S.V. Svechnikov and G. Wisz 96–98 (1996) 881

Etching

Photon-induced dry etching of Si(100) in the VUV, U. Streller, B. Li, A. Krabbe and N. Schwentner 96–98 (1996) 448
The role of gas-phase in the laser etching of Cu by CCl_4, D. Débarre, A. Aliouchouche, J. Boulmer, B. Bourguignon and J.P. Budin 96–98 (1996) 453
Fast etching of sapphire by a visible range quasi-cw laser radiation, S.I. Dolgaev, A.A. Lyalin, A.V. Simakin and G.A. Shafeev 96–98 (1996) 491
CCl_4-assisted CF_4 etching of silicon in a microwave-assisted LDE (laser dry etching)-process, W. Pfleging, D.A. Wesner and E.W. Kreutz 96–98 (1996) 496
Etching and functionalization of a fluorocarbon polymer by UV laser treatment, C. Girardeaux, Y. Idrissi, J.J. Pireaux and R. Caudano 96–98 (1996) 586

Evaporation

Excimer laser induced thermal evaporation and ablation of silicon carbide, R. Reitano, P. Baeri and N. Marino 96–98 (1996) 302

Fluorescence

Laser implantation of fluorescent molecules into polymer films, H. Fukumura, Y. Kohji and H. Masuhara 96–98 (1996) 569

Gallium

Soft laser sputtering of the GaAlAs (100) surface, L. Vivet, B. Dubreuil, T. Gibert-Legrand and M.F. Barthe 96–98 (1996) 238
Laser induced nitridation of Ga on GaAs surfaces, M.F. Barthe, C. Perrin, L. Vivet, B. Dubreuil and T. Gibert 96–98 (1996) 359

Gallium arsenide

Laser induced nitridation of Ga on GaAs surfaces, M.F. Barthe, C. Perrin, L. Vivet, B. Dubreuil and T. Gibert 96–98 (1996) 359
Micro-Raman study of UV laser ablation of GaAs and Si substrates, C. García, J. Ramos, A.C. Prieto, J. Jiménez, C. Geertsen, J.L. Lacour and P. Mauchien 96–98 (1996) 370

Germanium

Analytical description of the film thickness distribution obtained by the pulsed laser ablation of a monoatomic target: application to silicon and germanium, F. Antoni, C. Fuchs and E. Fogarassy 96–98 (1996) 50

Glass

Excimer laser ablation of polymers and glasses for grating fabrication, P.E. Dyer, R.J. Farley, R. Giedl and D.M. Karnakis 96–98 (1996) 537
Rare-earth doped glass waveguides prepared by pulsed laser deposition, C.N. Afonso, J.M. Ballesteros, J. Gonzalo, G.C. Righini and S. Pelli 96–98 (1996) 760

Gold

Picosecond UV-laser ablation of Au and Ni films, A. Rosenfeld and E.E.B. Campbell 96–98 (1996) 439

Graphite

Formation of large carbon cluster ions at graphite (HOPG) surfaces by laser irradiation, H. Togashi, K. Saito, Y. Koga, H. Yamawaki, K. Aoki, M. Mukaida and T. Kameyama 96–98 (1996) 267

Halogenides

CCl_4-assisted CF_4 etching of silicon in a microwave-assisted LDE (laser dry etching)-process, W. Pfleging, D.A. Wesner and E.W. Kreutz 96–98 (1996) 496

Indium

Low-fluence excimer laser irradiation-induced defect formation in indium–tin oxide films, T. Szörényi, L.D. Laude, I. Bertóti, Zs. Geretovszky and Z. Kántor 96–98 (1996) 363
Pulsed laser deposition of high quality ITO thin films, F. Hanus, A. Jadin and L.D. Laude 96–98 (1996) 807

Infrared spectroscopy

Chemical surface modification of fluorocarbon polymers by excimer laser processing, H. Niino and A. Yabe 96–98 (1996) 550
Pulsed laser ablation and deposition of fluorocarbon polymers, M.G. Norton, W. Jiang, J.T. Dickinson and K.W. Hipps 96–98 (1996) 617

Ion bombardment

Ion-assisted pulsed-laser deposition for the fabrication of Y–Ba–Cu–O multilayer structures using oriented intermediate layers of YSZ and CeO_2, R.P. Reade and R.E. Russo 96–98 (1996) 726

Ion scattering

Electrical characterization of semiconducting La doped $SrTiO_3$ thin films prepared by pulsed laser deposition, K.-O. Grosse-Holz, J.F.M. Cillessen and R. Waser 96–98 (1996) 784
Laser reactive ablation deposition of silicon carbide films, G. Leggieri, A. Luches, M. Martino, A. Perrone, R. Alexandrescu, A. Barborica, E. Gyorgy, I.N. Mihailescu, G. Majni and P. Mengucci 96–98 (1996) 866

Iron

Measurement and calculation of the Fe_2O_3 ablation depth, A. Lisfi, M. Guyot, R. Krishnan and V. Cagan 96–98 (1996) 66
Laser induced periodic surface structures on iron, A. Dauscher, V. Feregotto, P. Cordier and A. Thomy 96–98 (1996) 410

Langmuir–Blodgett structures

Mapping of molecular C_{17} indandione-1,3 pyridinium betaine adsorbates on fused silica by surface second harmonic generation, D. Ding, T. Käämbre, S. Ljungström, Y. Chen, K. Siegbahn, E. Wistus, P. Swensson and E. Mukhtar 96–98 (1996) 581

Laser processing

Microscopic and mesoscopic aspects of laser-induced desorption and ablation, R.F. Haglund, Jr. 96–98 (1996) 1
Hydrodynamic phenomena during laser irradiation: a finite difference approach, N. Seifert, G. Betz and W. Husinsky 96–98 (1996) 33
Measurement and calculation of the Fe_2O_3 ablation depth, A. Lisfi, M. Guyot, R. Krishnan and V. Cagan 96–98 (1996) 66
Calculation and measurement of the ultrasonic signals generated by ablating material with a Q-switched pulse laser, A. Hoffmann and W. Arnold 96–98 (1996) 71
2D-simulation of the system: laser beam + laser plasma + target, V.I. Mazhukin, I. Smurov and G. Flamant 96–98 (1996) 89
Modeling of laser induced plasma, spectroscopic and time of flight experiments in pulsed laser deposition, G. Granse, S. Völlmar, A. Lenk, A. Rupp and K. Rohr 96–98 (1996) 97
Study of the expansion of the laser ablation plume above a boron nitride target, B. Angleraud, C. Girault, C. Champeaux, F. Garrelie, C. Germain and A. Catherinot 96–98 (1996) 117
Preferential vaporization and plasma shielding during nano-second laser ablation, X. Mao, W.-T. Chan, M. Caetano, M.A. Shannon and R.E. Russo 96–98 (1996) 126
Laser ablation plume thermalization dynamics in background gases: combined imaging, optical absorption and emission spectroscopy, and ion probe measurements, D.B. Geohegan and A.A. Puretzky 96–98 (1996) 131
Fundamental characteristics of laser–material interactions (ablation) in noble gases at atmospheric pressure using inductively coupled plasma-atomic emission spectroscopy, R.E. Russo, X.L. Mao, M. Caetano and M.A. Shannon 96–98 (1996) 144
Monitoring stress power during high-power pulsed laser–material interactions, M.A. Shannon and R.E. Russo 96–98 (1996) 149
Spatially and temporally resolved emission intensities and number densities in low temperature laser-induced plasmas in vacuum and in ambient gases, R.A. Al-Wazzan, J.M. Hendron and T. Morrow 96–98 (1996) 170
Laser produced plasmas in high fluence ablation of metallic surfaces probed by time-of-flight mass spectrometry, S. Amoruso, A. Amodeo, V. Berardi, R. Bruzzese, N. Spinelli and R. Velotta 96–98 (1996) 175
Optical diagnostics of the laser–target and laser–plume interaction in pulsed laser ablation, F. Fuso, L.N. Vyacheslavov, G. Lorenzi, M. Allegrini and E. Arimondo 96–98 (1996) 181
Time-of-flight characterization of laser ablation plume from $NbTe_2$ target in He atmosphere, F. Grangeon, H. Sassoli, W. Marine and M. Autric 96–98 (1996) 186

Investigation of vaporization and condensation processes of thin layers of CdHgTe from laser erosion plasma in Hg atmosphere, B.K. Kotlyarchuk, D.I. Popovych, V.K. Savchuk and V.G. Savitsky 96–98 (1996) 192
Density and electron temperature of laser induced plasma – a comparison of different investigation methods, A. Lenk, Th. Witke and G. Granse 96–98 (1996) 195
Comments on explosive mechanisms of laser sputtering, R. Kelly and A. Miotello 96–98 (1996) 205
Analysis of the expansion of hydroxyapatite laser ablation plumes, P. Serra, L. Clèries and J.L. Morenza 96–98 (1996) 216
Dynamics of silicon plume generated by laser ablation and its chemical reaction, T. Makimura and K. Murakami 96–98 (1996) 242
Formation of large carbon cluster ions at graphite (HOPG) surfaces by laser irradiation, H. Togashi, K. Saito, Y. Koga, H. Yamawaki, K. Aoki, M. Mukaida and T. Kameyama 96–98 (1996) 267
Excimer laser induced surface modifications and matter interaction using double-pulse-technique (DPT), H.W. Bergmann 96–98 (1996) 287
Excimer laser-induced hydrodynamical effects and surface modifications on silicon carbide, G. Nicolas and M. Autric 96–98 (1996) 296
Excimer laser induced thermal evaporation and ablation of silicon carbide, R. Reitano, P. Baeri and N. Marino 96–98 (1996) 302
Increase of efficiency for the XeCl excimer laser ablation of ceramics, M. Geiger, W. Becker, T. Rebhan, J. Hutfless and N. Lutz 96–98 (1996) 309
The role of defects in laser induced positive ion emission from ionic crystals, J.T. Dickinson, J.-J. Shin and S.C. Langford 96–98 (1996) 316
Laser-induced emission of neutral atoms and molecules from electron-irradiated $NaNO_3$, J.T. Dickinson, J.J. Shin and S.C. Langford 96–98 (1996) 326
Laser damage of $CaF_2(111)$ surfaces at 248 nm, S. Gogoll, E. Stenzel, M. Reichling, H. Johansen and E. Matthias 96–98 (1996) 332
Laser patterning of thin-film electrochemical gas sensors, A. Lecours, M. Caron, P. Ciureanu, G. Turcotte, D. Ivanov, A. Yelon and J.F. Currie 96–98 (1996) 341
Laser beam application to thin film transistors, T. Sameshima 96–98 (1996) 352
Laser induced nitridation of Ga on GaAs surfaces, M.F. Barthe, C. Perrin, L. Vivet, B. Dubreuil and T. Gibert 96–98 (1996) 359
Low-fluence excimer laser irradiation-induced defect formation in indium–tin oxide films, T. Szörényi, L.D. Laude, I. Bertóti, Zs. Geretovszky and Z. Kántor 96–98 (1996) 363
Micro-Raman study of UV laser ablation of GaAs and Si substrates, C. García, J. Ramos, A.C. Prieto, J. Jiménez, Ç. Geertsen, J.L. Lacour and P. Mauchien 96–98 (1996) 370
Single shot excimer laser annealing of amorphous silicon for AMLCD, P. Boher, J.L. Stehle, M. Stehle and B. Godard 96–98 (1996) 376
Erosion plume dynamics during pulsed laser alloying, V. Titov, I. Smurov and M. Ignatiev 96–98 (1996) 387
Excimer laser interaction with dielectric thin films, E. Welsch, K. Ettrich, H. Blaschke and N. Kaiser 96–98 (1996) 393
Decomposition mechanisms of thin palladium acetate film with excimer UV radiation, J.-Y. Zhang, H. Esrom and I.W. Boyd 96–98 (1996) 399
Single crystal laser patterning for selective $YBa_2Cu_3O_{7-x}$ growth, R. Aguiar, F. Sánchez and M. Varela 96–98 (1996) 405
Laser induced periodic surface structures on iron, A. Dauscher, V. Feregotto, P. Cordier and A. Thomy 96–98 (1996) 410
Excimer laser ablation for micro-machining: geometric effects, P.E. Dyer, D.M. Karnakis, P.H. Key and P. Monk 96–98 (1996) 415
Optodynamics of laser ablation of graduation lines in chromium thin film on glass, S. Kopač, J. Pirš and J. Možina 96–98 (1996) 420
Excimer laser machining for the fabrication of analogous microstructures, K. Zimmer, D. Hirsch and F. Bigl 96–98 (1996) 425
Femtosecond-pulse visible laser processing of transparent materials, J. Krüger and W. Kautek 96–98 (1996) 430
Picosecond UV-laser ablation of Au and Ni films, A. Rosenfeld and E.E.B. Campbell 96–98 (1996) 439
The role of gas-phase in the laser etching of Cu by CCl_4, D. Débarre, A. Aliouchouche, J. Boulmer, B. Bourguignon and J.P. Budin 96–98 (1996) 453
Laser-induced formation of visible light emitting silicon, D. Dimova-Malinovska, M. Tzolov, N. Malinowski, Ts. Marinova and V. Krastev 96–98 (1996) 457
Cleaning of optical surfaces by excimer laser radiation, K. Mann, B. Wolff-Rottke and F. Müller 96–98 (1996) 463
In situ surface cleaning of pure and implanted tungsten photocathodes by pulsed laser irradiation, M. Afif, J.P. Girardeau-Montaut, C. Tomas, M. Romand, M. Charbonnier, N.S. Prakash, A. Perez, G. Marest and J.M. Frigerio 96–98 (1996) 469
Laser cleaning in art restoration, I. Gobernado-Mitre, J. Medina, B. Calvo, A.C.

Prieto, L.A. Leal, B. Pérez, F. Marcos and A.M. de Frutos 96–98 (1996) 474
Cleaning of copper traces on circuit boards with excimer laser radiation, D.A. Wesner, M. Mertin, F. Lupp and E.W. Kreutz 96–98 (1996) 479
Modelling and diagnostic of pulsed laser cleaning of oxidized metallic surfaces, R. Oltra, O. Yavaş, F. Cruz, J.P. Boquillon and C. Sartori 96–98 (1996) 484
Fast etching of sapphire by a visible range quasi-cw laser radiation, S.I. Dolgaev, A.A. Lyalin, A.V. Simakin and G.A. Shafeev 96–98 (1996) 491
Surface temperature measurements during pulsed laser action on metallic and ceramic materials, M.B. Ignatiev, I.Yu. Smurov, G. Flamant and V.N. Senchenko 96–98 (1996) 505
Real-time determination of the amount of removed material during short pulses laser micromachining, C. Stauter, J. Fontaine and Th. Engel 96–98 (1996) 522
White synchrotron X-radiation-section topography of high energy density ns-pulsed (Nd:YAG) ablation damage in Si(100) wafers, J.D. Stephenson 96–98 (1996) 528
Excimer laser ablation of polymers and glasses for grating fabrication, P.E. Dyer, R.J. Farley, R. Giedl and D.M. Karnakis 96–98 (1996) 537
Chemical surface modification of fluorocarbon polymers by excimer laser processing, H. Niino and A. Yabe 96–98 (1996) 550
Excimer laser-induced surface modifications of biocompatible polymer blends, P. Viville, S. Beauvois, G. Lambin, R. Lazzaroni, J.L. Brédas, K. Kolev and L. Laude 96–98 (1996) 558
Laser implantation of fluorescent molecules into polymer films, H. Fukumura, Y. Kohji and H. Masuhara 96–98 (1996) 569
Excited state relaxation processes of MALDI-matrices studied by luminescence spectroscopy, H. Ehring and B.U.R. Sundqvist 96–98 (1996) 577
Etching and functionalization of a fluorocarbon polymer by UV laser treatment, C. Girardeaux, Y. Idrissi, J.J. Pireaux and R. Caudano 96–98 (1996) 586
Optodynamic studies of Er:YAG laser induced microexplosions in dentin, L. Grad and J. Možina 96–98 (1996) 591
Single pulse threshold and transmission behaviour of a triazeno-polymer during pulsed UV-laser irradiation, T. Lippert, L.S. Bennett, T. Nakamura, H. Niino and A. Yabe 96–98 (1996) 601
Formation of the surface structure of polyethylene-terephtalate (PET) due to ArF excimer laser ablation, B. Hopp, M. Csete, K. Révész, J. Vinkó and Zs. Bor 96–98 (1996) 611
Thin film growth by the pulsed laser assisted deposition technique, C. Belouet 96–98 (1996) 630
Giant laser-induced voltages at room temperature in Pr doped Y–Ba–Cu–O thin films, H.-U. Habermeier, N. Jisrawi and G. Jäger-Waldau 96–98 (1996) 689
Laser ablation of oxides: study of the oxygen incorporation by ^{18}O isotopic tracing techniques, R. Pérez Casero, R. Gómez San Román, C. Maréchal, J.P. Enard and J. Perrière 96–98 (1996) 697
Substrate size effect at off-axis laser deposition of multicomponent films, M.R. Predtechensky, O.M. Tukhto, A.N. Smal' and S.A. Vasil'eva 96–98 (1996) 717
Reactive laser deposition of high quality YBaCuO and ErBaCuO films, D. Berling, A. Del Vecchio, S. Acquaviva, D. Bolmont, G. Leggieri, B. Loegel, M. Luisa De Giorgi, A. Luches, A. Mehdaoui and L. Tapfer 96–98 (1996) 739

Lead

$Pb_{1-x}Ca_xTiO_3$ thin films prepared by laser ablation of ceramic targets, M.J. Martín, C. Zaldo and J. Mendiola 96–98 (1996) 823

Luminescence

Optical spectroscopy of emission from Si–SiO_x nanoclusters formed by laser ablation, I.A. Movtchan, W. Marine, R.W. Dreyfus, H.C. Le, M. Sentis and M. Autric 96–98 (1996) 251
Laser-induced formation of visible light emitting silicon, D. Dimova-Malinovska, M. Tzolov, N. Malinowski, Ts. Marinova and V. Krastev 96–98 (1996) 457
Excited state relaxation processes of MALDI-matrices studied by luminescence spectroscopy, H. Ehring and B.U.R. Sundqvist 96–98 (1996) 577

Magnesium oxide

The role of defects in laser induced positive ion emission from ionic crystals, J.T. Dickinson, J.-J. Shin and S.C. Langford 96–98 (1996) 316

Magnetic structures

Ferrimagnetic thin films prepared by pulsed laser deposition, M. Guyot, A. Lisfi, R. Krishnan, M. Porte, P. Rougier and V. Cagan 96–98 (1996) 802
Pulsed Laser Deposition of permanent magnetic $Nd_2Fe_{14}B$ thin films, A.J.M. Geurtsen, J.C.S. Kools, L. de Wit and J.C. Lodder 96–98 (1996) 887

Mass spectroscopy

Transport of neutral atoms, monoxides and clusters in the plume produced by laser ablation of $YBa_2Cu_3O_{7-x}$ in oxygen environment, A.V. Bulgakov, M.R. Predtechensky and A.P. Mayorov 96–98 (1996) 159
Laser produced plasmas in high fluence ablation of metallic surfaces probed by time-of-flight mass spectrometry, S. Amoruso, A. Amodeo, V. Berardi, R. Bruzzese, N. Spinelli and R. Velotta 96–98 (1996) 175
Energy-dispersive mass spectrometry of high energy ions generated during KrF excimer and frequency-doubled Nd: YAG laser ablation of metals, G.C. Tyrrell, L.G. Coccia, T.H. York and I.W. Boyd 96–98 (1996) 227
Soft laser sputtering of the GaAlAs (100) surface, L. Vivet, B. Dubreuil, T. Gibert-Legrand and M.F. Barthe 96–98 (1996) 238
Magnetic field enhanced growth of carbon cluster ions in the laser ablation plume of graphite, F. Kokai, Y. Koga and R.B. Heimann 96–98 (1996) 261
Formation of large carbon cluster ions at graphite (HOPG) surfaces by laser irradiation, H. Togashi, K. Saito, Y. Koga, H. Yamawaki, K. Aoki, M. Mukaida and T. Kameyama 96–98 (1996) 267
The role of defects in laser induced positive ion emission from ionic crystals, J.T. Dickinson, J.-J. Shin and S.C. Langford 96–98 (1996) 316
Laser-induced emission of neutral atoms and molecules from electron-irradiated $NaNO_3$, J.T. Dickinson, J.J. Shin and S.C. Langford 96–98 (1996) 326
Decomposition mechanisms of thin palladium acetate film with excimer UV radiation, J.-Y. Zhang, H. Esrom and I.W. Boyd 96–98 (1996) 399
CCl_4-assisted CF_4 etching of silicon in a microwave-assisted LDE (laser dry etching)-process, W. Pfleging, D.A. Wesner and E.W. Kreutz 96–98 (1996) 496
Excited state relaxation processes of MALDI-matrices studied by luminescence spectroscopy, H. Ehring and B.U.R. Sundqvist 96–98 (1996) 577
High sensitivity quadrupole mass spectrometry of neutrals sputtered by UV-laser ablation of polymers, S. Lazare, W. Guan and D. Drilhole 96–98 (1996) 605

Mercury

Investigation of vaporization and condensation processes of thin layers of CdHgTe from laser erosion plasma in Hg atmosphere, B.K. Kotlyarchuk, D.I. Popovych, V.K. Savchuk and V.G. Savitsky 96–98 (1996) 192
Deposition of HgCdTe epitaxial layers on anisotropically etched silicon surfaces by laser evaporation, T.Ya. Gorbach, M. Kuźma, E. Sheregii, P.S. Smertenko, S.V. Svechnikov and G. Wisz 96–98 (1996) 881

Metals

Optical diagnostics of the laser–target and laser–plume interaction in pulsed laser ablation, F. Fuso, L.N. Vyacheslavov, G. Lorenzi, M. Allegrini and E. Arimondo 96–98 (1996) 181
Laser ablation of metals: the transition from non-thermal processes to thermal evaporation, T. Götz, M. Bergt, W. Hoheisel, F. Träger and M. Stuke 96–98 (1996) 280
Surface temperature measurements during pulsed laser action on metallic and ceramic materials, M.B. Ignatiev, I.Yu. Smurov, G. Flamant and V.N. Senchenko 96–98 (1996) 505
Pulsed laser deposition of novel materials for thin film solid oxide fuel cell applications: $Ce_{0.9}Gd_{0.1}O_{1.95}$, $La_{0.7}Sr_{0.3}CoO_y$ and $La_{0.7}Sr_{0.3}Co_{0.2}Fe_{0.8}O_y$, L.G. Coccia, G.C. Tyrrell, J.A. Kilner, D. Waller, R.J. Chater and I.W. Boyd 96–98 (1996) 795

Multilayers

Excimer laser interaction with dielectric thin films, E. Welsch, K. Ettrich, H. Blaschke and N. Kaiser 96–98 (1996) 393
Ultrathin film deposition by pulsed laser ablation using crossed beams, A.A. Gorbunov, W. Pompe, A. Sewing, S.V. Gaponov, A.D. Akhsakhalyan, I.G. Zabrodin, I.A. Kas'kov, E.B. Klyenkov, A.P. Morozov, N.N. Salaschenko, R. Dietsch, H. Mai and S. Völlmar 96–98 (1996) 649

Ion-assisted pulsed-laser deposition for the fabrication of Y–Ba–Cu–O multilayer structures using oriented intermediate layers of YSZ and CeO_2, R.P. Reade and R.E. Russo 96–98 (1996) 726

Nickel

Picosecond UV-laser ablation of Au and Ni films, A. Rosenfeld and E.E.B. Campbell 96–98 (1996) 439

Niobium

Time-of-flight characterization of laser ablation plume from $NbTe_2$ target in He atmosphere, F. Grangeon, H. Sassoli, W. Marine and M. Autric 96–98 (1996) 186

Nitric oxide

Laser-induced emission of neutral atoms and molecules from electron-irradiated $NaNO_3$, J.T. Dickinson, J.J. Shin and S.C. Langford 96–98 (1996) 326

Nitrides

Laser induced nitridation of Ga on GaAs surfaces, M.F. Barthe, C. Perrin, L. Vivet, B. Dubreuil and T. Gibert 96–98 (1996) 359
Carbon nitride thin films obtained by laser ablation of graphite in a nitrogen plasma, M.C. Polo, R. Aguiar, P. Serra, L. Clèries, M. Varela and J. Esteve 96–98 (1996) 870

Optical properties

Electrostatic probe and optical spectroscopy studies of low temperature laser produced plasmas, J.M. Hendron, R.A. Al-Wazzan, C. Mahony, T. Morrow and W.G. Graham 96–98 (1996) 112
Optical spectroscopy of emission from Si–SiO_x nanoclusters formed by laser ablation, I.A. Movtchan, W. Marine, R.W. Dreyfus, H.C. Le, M. Sentis and M. Autric 96–98 (1996) 251
Excimer laser interaction with dielectric thin films, E. Welsch, K. Ettrich, H. Blaschke and N. Kaiser 96–98 (1996) 393
Electrical and optical characteristics of organic thin films fabricated by laser ablation, T. Fujii, H. Shima, N. Matsumoto and F. Kannari 96–98 (1996) 625
In-situ reflectivity measurements during pulsed-laser deposition of $Bi_2Sr_2CaCu_2O_{8+\delta}$, A. Ritzer, B. Falkner, S.T. Li and D. Bäuerle 96–98 (1996) 721
Deposition of optical coatings by pulsed laser ablation, G. Reisse, S. Weissmantel, B. Keiper and U. Broulik 96–98 (1996) 752

Organic substances

Electrical and optical characteristics of organic thin films fabricated by laser ablation, T. Fujii, H. Shima, N. Matsumoto and F. Kannari 96–98 (1996) 625

Oxidation

Etching and functionalization of a fluorocarbon polymer by UV laser treatment, C. Girardeaux, Y. Idrissi, J.J. Pireaux and R. Caudano 96–98 (1996) 586

Oxides

Measurement and calculation of the Fe_2O_3 ablation depth, A. Lisfi, M. Guyot, R. Krishnan and V. Cagan 96–98 (1996) 66
Off-axis excimer laser deposition of Ta_2O_5 thin films, N. Inoue, S. Kashiwabara, S. Toshima and R. Fujimoto 96–98 (1996) 656
Stoichiometric transfer of complex oxides by pulsed laser deposition, B. Dam, J.H. Rector, J. Johansson, S. Kars and R. Griessen 96–98 (1996) 679
Laser ablation of oxides: study of the oxygen incorporation by ^{18}O isotopic tracing techniques, R. Pérez Casero, R. Gómez San Román, C. Maréchal, J.P. Enard and J. Perrière 96–98 (1996) 697
Growth, structuring and characterisation of all-oxide thin film devices prepared by pulsed laser deposition, J.F.M. Cillessen, R.M. Wolf, J.B. Giesbers, P.W.M. Blom, K.-O. Grosse-Holz and E. Pastoor 96–98 (1996) 744
Epitaxial ferroelectric PZT and BST thin films by pulsed UV laser deposition, C. Champeaux, P. Marchet and A. Catherinot 96–98 (1996) 775
Pulsed laser deposition of sillenite films intended for photorefractive damage free waveguides, J.E. Alfonso, M.J. Martín, J. Mendiola, K. Polgár and C. Zaldo 96–98 (1996) 791
Pulsed laser deposition of novel materials for thin film solid oxide fuel cell applications: $Ce_{0.9}Gd_{0.1}O_{1.95}$, $La_{0.7}Sr_{0.3}$-

CoO_y and $La_{0.7}Sr_{0.3}Co_{0.2}Fe_{0.8}O_y$, L.G. Coccia, G.C. Tyrrell, J.A. Kilner, D. Waller, R.J. Chater and I.W. Boyd 96–98 (1996) 795
Excimer laser ablating preparation of $Ba_2NaNb_5O_{15}$ thin films on $KTiOPO_4$ substrate and its guide wave property, J.M. Liu, Z.G. Liu, S.N. Zhu, Y.Y. Zhu and N.B. Ming 96–98 (1996) 819
$Pb_{1-x}Ca_xTiO_3$ thin films prepared by laser ablation of ceramic targets, M.J. Martín, C. Zaldo and J. Mendiola 96–98 (1996) 823

Oxygen

Laser-induced emission of neutral atoms and molecules from electron-irradiated $NaNO_3$, J.T. Dickinson, J.J. Shin and S.C. Langford 96–98 (1996) 326
Laser ablation of oxides: study of the oxygen incorporation by ^{18}O isotopic tracing techniques, R. Pérez Casero, R. Gómez San Román, C. Maréchal, J.P. Enard and J. Perrière 96–98 (1996) 697

Palladium

Decomposition mechanisms of thin palladium acetate film with excimer UV radiation, J.-Y. Zhang, H. Esrom and I.W. Boyd 96–98 (1996) 399

Photodesorption

Microscopic and mesoscopic aspects of laser-induced desorption and ablation, R.F. Haglund, Jr. 96–98 (1996) 1

Photoelectron spectroscopy

Low-fluence excimer laser irradiation-induced defect formation in indium–tin oxide films, T. Szörényi, L.D. Laude, I. Bertóti, Zs. Geretovszky and Z. Kántor 96–98 (1996) 363
Laser-induced formation of visible light emitting silicon, D. Dimova-Malinovska, M. Tzolov, N. Malinowski, Ts. Marinova and V. Krastev 96–98 (1996) 457
Cleaning of copper traces on circuit boards with excimer laser radiation, D.A. Wesner, M. Mertin, F. Lupp and E.W. Kreutz 96–98 (1996) 479
CCl_4-assisted CF_4 etching of silicon in a microwave-assisted LDE (laser dry etching)-process, W. Pfleging, D.A. Wesner and E.W. Kreutz 96–98 (1996) 496
Chemical surface modification of fluorocarbon polymers by excimer laser processing, H. Niino and A. Yabe 96–98 (1996) 550
Etching and functionalization of a fluorocarbon polymer by UV laser treatment, C. Girardeaux, Y. Idrissi, J.J. Pireaux and R. Caudano 96–98 (1996) 586
Deposition of fluoropolymer thin films containing semiconductor microcrystallites by VUV laser ablation, T. Fujii, S. Inoue and F. Kannari 96–98 (1996) 621
Electrical and optical characteristics of organic thin films fabricated by laser ablation, T. Fujii, H. Shima, N. Matsumoto and F. Kannari 96–98 (1996) 625
Excimer laser ablating preparation of $Ba_2NaNb_5O_{15}$ thin films on $KTiOPO_4$ substrate and its guide wave property, J.M. Liu, Z.G. Liu, S.N. Zhu, Y.Y. Zhu and N.B. Ming 96–98 (1996) 819
Pulsed laser deposition of electroceramic thin films, M. Mertin, D. Offenberg, C.W. An, D.A. Wesner and E.W. Kreutz 96–98 (1996) 842
Pulsed laser deposition of nasicon thin films, R. Izquierdo, F. Hanus, Th. Lang, D. Ivanov, M. Meunier, L. Laude, J.F. Currie and A. Yelon 96–98 (1996) 855
Laser reactive ablation deposition of silicon carbide films, G. Leggieri, A. Luches, M. Martino, A. Perrone, R. Alexandrescu, A. Barborica, E. Gyorgy, I.N. Mihailescu, G. Majni and P. Mengucci 96–98 (1996) 866

Photoemission

Laser-induced emission of neutral atoms and molecules from electron-irradiated $NaNO_3$, J.T. Dickinson, J.J. Shin and S.C. Langford 96–98 (1996) 326

Photoexcitation

Laser ablation of sodium nitrate: NO desorption following excitation of the $\pi-\pi^*$ band of the nitrate anion, W.P. Hess, K.A.H. German, R.A. Bradley and M.I. McCarthy 96–98 (1996) 321

Photon emission

Spatially and temporally resolved emission intensities and number densities in low temperature laser-induced plasmas in vacuum and in ambient gases, R.A. Al-Wazzan, J.M. Hendron and T. Morrow 96–98 (1996) 170

Plasma processing

Laser plasma threshold of metals, S. Petzoldt, J. Reif and E. Matthias 96–98 (1996) 199

Optical and particle properties of PLD vapour/plasmas of ceramics, M. Alunovic, H. Stamm, M. Aden and E.W. Kreutz 96–98 (1996) 222

Spectroscopic study of the microwave plasma enhanced pulsed laser deposition for $Y_1Ba_2Cu_3O_{7-x}$ superconducting thin films, B.C. Chung, C.H. Tsai, S.S. Hsu, C.S. Huang, T.Y. Tseng and I.N. Lin 96–98 (1996) 233

X-ray generation for medical applications from a laser-produced plasma, M. Grätz, C. Tillman, I. Mercer and S. Svanberg 96–98 (1996) 443

VUV ablation of polymers by emission from gas-puff Z-pinch plasmas, H. Deno, S. Sugiyama, Y. Kakudate, M. Yoshida and S. Fujiwara 96–98 (1996) 563

Mirror-smooth $YBa_2Cu_3O_{7-x}$ superconducting films deposited by plasma-enhanced pulsed laser deposition technique, C.S. Huang, T.Y. Tseng, B.C. Chung, C.H. Tsai, H.F. Cheng and I.N. Lin 96–98 (1996) 735

Polymers

Excimer laser ablation of polymers and glasses for grating fabrication, P.E. Dyer, R.J. Farley, R. Giedl and D.M. Karnakis 96–98 (1996) 537

Chemical surface modification of fluorocarbon polymers by excimer laser processing, H. Niino and A. Yabe 96–98 (1996) 550

Excimer laser-induced surface modifications of biocompatible polymer blends, P. Viville, S. Beauvois, G. Lambin, R. Lazzaroni, J.L. Brédas, K. Kolev and L. Laude 96–98 (1996) 558

VUV ablation of polymers by emission from gas-puff Z-pinch plasmas, H. Deno, S. Sugiyama, Y. Kakudate, M. Yoshida and S. Fujiwara 96–98 (1996) 563

Laser implantation of fluorescent molecules into polymer films, H. Fukumura, Y. Kohji and H. Masuhara 96–98 (1996) 569

Surface chemical reaction of polymer film with reactive intermediates produced by laser ablation of azido compound, H. Niino and A. Yabe 96–98 (1996) 572

Etching and functionalization of a fluorocarbon polymer by UV laser treatment, C. Girardeaux, Y. Idrissi, J.J. Pireaux and R. Caudano 96–98 (1996) 586

Excimer laser ablation of low and high absorption index polymers, P.E. Dyer, D.M. Karnakis, P.H. Key and J.P. Tait 96–98 (1996) 596

Single pulse threshold and transmission behaviour of a triazeno-polymer during pulsed UV-laser irradiation, T. Lippert, L.S. Bennett, T. Nakamura, H. Niino and A. Yabe 96–98 (1996) 601

High sensitivity quadrupole mass spectrometry of neutrals sputtered by UV-laser ablation of polymers, S. Lazare, W. Guan and D. Drilhole 96–98 (1996) 605

Formation of the surface structure of polyethylene-terephtalate (PET) due to ArF excimer laser ablation, B. Hopp, M. Csete, K. Révész, J. Vinkó and Zs. Bor 96–98 (1996) 611

Pulsed laser ablation and deposition of fluorocarbon polymers, M.G. Norton, W. Jiang, J.T. Dickinson and K.W. Hipps 96–98 (1996) 617

Deposition of fluoropolymer thin films containing semiconductor microcrystallites by VUV laser ablation, T. Fujii, S. Inoue and F. Kannari 96–98 (1996) 621

Pulsed laser deposition

Modeling of dynamical processes in laser ablation, J.N. Leboeuf, K.R. Chen, J.M. Donato, D.B. Geohegan, C.L. Liu, A.A. Puretzky and R.F. Wood 96–98 (1996) 14

Material removal and plasmadynamics during pulsed laser deposition by excimer and CO_2 laser radiation, M. Aden and E.W. Kreutz 96–98 (1996) 39

Analytical description of the film thickness distribution obtained by the pulsed laser ablation of a monoatomic target: application to silicon and germanium, F. Antoni, C. Fuchs and E. Fogarassy 96–98 (1996) 50

Calculations and experiments of material removal and kinetic energy during pulsed laser ablation of metals, S. Fähler and H.-U. Krebs 96–98 (1996) 61

Modeling of laser induced plasma, spectroscopic and time of flight experiments in pulsed laser deposition, G. Granse, S. Völlmar, A. Lenk, A. Rupp and K. Rohr 96–98 (1996) 97

Plasma parameters in pulsed laser-plasma deposition of thin films, S. Metev, M. Ozegowski, G. Sepold and S. Burmester 96–98 (1996) 122

Electromagnetic diagnostics during pulsed laser deposition, A.V. Kabashin, W. Marine, P.I. Nikitin and M. Sentis 96–98 (1996) 139

Optical and particle properties of PLD vapour/plasmas of ceramics, M. Alunovic, H. Stamm, M. Aden and E.W. Kreutz 96–98 (1996) 222

Spectroscopic study of the microwave plasma enhanced pulsed laser deposition for $Y_1Ba_2Cu_3O_{7-x}$ superconducting thin films, B.C. Chung, C.H. Tsai, S.S. Hsu, C.S. Huang, T.Y. Tseng and I.N. Lin 96–98 (1996) 233
Surface chemical reaction of polymer film with reactive intermediates produced by laser ablation of azido compound, H. Niino and A. Yabe 96–98 (1996) 572
Pulsed laser ablation and deposition of fluorocarbon polymers, M.G. Norton, W. Jiang, J.T. Dickinson and K.W. Hipps 96–98 (1996) 617
Deposition of fluoropolymer thin films containing semiconductor microcrystallites by VUV laser ablation, T. Fujii, S. Inoue and F. Kannari 96–98 (1996) 621
Electrical and optical characteristics of organic thin films fabricated by laser ablation, T. Fujii, H. Shima, N. Matsumoto and F. Kannari 96–98 (1996) 625
Thin film growth by the pulsed laser assisted deposition technique, C. Belouet 96–98 (1996) 630
Scale-up of pulsed laser deposition (PLD) for 4″-wafer coating, M. Panzner, R. Dietsch, Th. Holz, H. Mai and S. Völlmar 96–98 (1996) 643
Ultrathin film deposition by pulsed laser ablation using crossed beams, A.A. Gorbunov, W. Pompe, A. Sewing, S.V. Gaponov, A.D. Akhsakhalyan, I.G. Zabrodin, I.A. Kas'kov, E.B. Klyenkov, A.P. Morozov, N.N. Salaschenko, R. Dietsch, H. Mai and S. Völlmar 96–98 (1996) 649
Off-axis excimer laser deposition of Ta_2O_5 thin films, N. Inoue, S. Kashiwabara, S. Toshima and R. Fujimoto 96–98 (1996) 656
Aspects of particulate production from metals exposed to pulsed laser radiation, I. Weaver and C.L.S. Lewis 96–98 (1996) 663
Classification of particulates on pulsed-laser deposited Y–Ba–Cu–O films, S. Proyer, E. Stangl, M. Borz and D. Bäuerle 96–98 (1996) 668
Formation of artificially-layered high-temperature superconductors using pulsed-laser deposition, D.P. Norton, B.C. Chakoumakos, D.H. Lowndes and J.D. Budai 96–98 (1996) 672
Stoichiometric transfer of complex oxides by pulsed laser deposition, B. Dam, J.H. Rector, J. Johansson, S. Kars and R. Griessen 96–98 (1996) 679
Improved properties of Pulsed Laser Deposited YBaCuO on $NdGaO_3$ using CeO_2 template layers, D.H.A. Blank, A.J.H.M. Rijnders, F.J.G. Roesthuis, G. den Ouden and H. Rogalla 96–98 (1996) 685
The importance of gas scattering processes on the stoichiometry deviations of laser deposited films, J. Gonzalo, C.N. Afonso, J. Perrière and R. Gómez San Roman 96–98 (1996) 693
Critical thickness of YBaCuO (123) strained thin films and superlattices grown by pulsed laser deposition, A. Abert, J.P. Contour, A. Défossez, D. Ravelosona, W. Schwegle and P. Ziemann 96–98 (1996) 703
Laser deposition of $YBa_2Cu_3O_7$ films on MgO(100) at 100 mm target–substrate distance and oxygen pressures below 0.1 mbar, F. Goerke, A. Thorns and U. Merkt 96–98 (1996) 708
Anisotropic resistivity in pulsed-laser deposited $Bi_2Sr_2CaCu_2O_{8+\delta}$ films, S.T. Li, A. Ritzer, S. Proyer, E. Stangl, D. Bäuerle and N. Reschauer 96–98 (1996) 713
In-situ reflectivity measurements during pulsed-laser deposition of $Bi_2Sr_2CaCu_2O_{8+\delta}$, A. Ritzer, B. Falkner, S.T. Li and D. Bäuerle 96–98 (1996) 721
Ion-assisted pulsed-laser deposition for the fabrication of Y–Ba–Cu–O multilayer structures using oriented intermediate layers of YSZ and CeO_2, R.P. Reade and R.E. Russo 96–98 (1996) 726
Synthesis of RE–Ba–Sr–Cu–O by pulsed-laser deposition, E. Stangl, S. Proyer, B. Hellebrand and D. Bäuerle 96–98 (1996) 731
Mirror-smooth $YBa_2Cu_3O_{7-x}$ superconducting films deposited by plasma-enhanced pulsed laser deposition technique, C.S. Huang, T.Y. Tseng, B.C. Chung, C.H. Tsai, H.F. Cheng and I.N. Lin 96–98 (1996) 735
Growth, structuring and characterisation of all-oxide thin film devices prepared by pulsed laser deposition, J.F.M. Cillessen, R.M. Wolf, J.B. Giesbers, P.W.M. Blom, K.-O. Grosse-Holz and E. Pastoor 96–98 (1996) 744
Deposition of optical coatings by pulsed laser ablation, G. Reisse, S. Weissmantel, B. Keiper and U. Broulik 96–98 (1996) 752
Rare-earth doped glass waveguides prepared by pulsed laser deposition, C.N. Afonso, J.M. Ballesteros, J. Gonzalo, G.C. Righini and S. Pelli 96–98 (1996) 760
Preparation of SiO_xN_y films by reactive KrF laser ablation, K. Maruyama, Y. Aoki, M. Matsumoto, Y. Hiroshima and H. Ohta 96–98 (1996) 764
Kinetic energy distributions of ions ejected during laser ablation of lead zirconate titanate and their correlation to deposi-

tion of ferroelectric thin films, G.C. Tyrrell, T.H. York, L.G. Coccia and I.W. Boyd 96–98 (1996) 769
Epitaxial ferroelectric PZT and BST thin films by pulsed UV laser deposition, C. Champeaux, P. Marchet and A. Catherinot 96–98 (1996) 775
Growth and characterization of PLZT films, M.J.M. Gomes, E. de Matos Gomes, P.L.Q. Mantas and J.L. Baptista 96–98 (1996) 779
Electrical characterization of semiconducting La doped $SrTiO_3$ thin films prepared by pulsed laser deposition, K.-O. Grosse-Holz, J.F.M. Cillessen and R. Waser 96–98 (1996) 784
Pulsed laser deposition of sillenite films intended for photorefractive damage free waveguides, J.E. Alfonso, M.J. Martín, J. Mendiola, K. Polgár and C. Zaldo 96–98 (1996) 791
Pulsed laser deposition of novel materials for thin film solid oxide fuel cell applications: $Ce_{0.9}Gd_{0.1}O_{1.95}$, $La_{0.7}Sr_{0.3}CoO_y$ and $La_{0.7}Sr_{0.3}Co_{0.2}Fe_{0.8}O_y$, L.G. Coccia, G.C. Tyrrell, J.A. Kilner, D. Waller, R.J. Chater and I.W. Boyd 96–98 (1996) 795
Ferrimagnetic thin films prepared by pulsed laser deposition, M. Guyot, A. Lisfi, R. Krishnan, M. Porte, P. Rougier and V. Cagan 96–98 (1996) 802
Pulsed laser deposition of high quality ITO thin films, F. Hanus, A. Jadin and L.D. Laude 96–98 (1996) 807
Pulsed-laser deposited ZnO for device applications, S.L. King, J.G.E. Gardeniers and I.W. Boyd 96–98 (1996) 811
$Pb_{1-x}Ca_xTiO_3$ thin films prepared by laser ablation of ceramic targets, M.J. Martín, C. Zaldo and J. Mendiola 96–98 (1996) 823
Characterization of ZnO thin films deposited by laser ablation in reactive atmosphere, P. Verardi, M. Dinescu and A. Andrei 96–98 (1996) 827
An experimental study and modeling of the thickness distribution in pulsed laser deposited ferroelectric thin films, M. Tyunina, K. Sreenivas, C. Bjormander, J. Wittborn and K.V. Rao 96–98 (1996) 831
Preparation of TiO_2 thin films by pulsed laser deposition for waveguiding applications, C. Garapon, C. Champeaux, J. Mugnier, G. Panczer, P. Marchet, A. Catherinot and B. Jacquier 96–98 (1996) 836
Pulsed laser deposition of electroceramic thin films, M. Mertin, D. Offenberg, C.W. An, D.A. Wesner and E.W. Kreutz 96–98 (1996) 842
Pulsed laser deposition of nasicon thin films, R. Izquierdo, F. Hanus, Th. Lang, D. Ivanov, M. Meunier, L. Laude, J.F. Currie and A. Yelon 96–98 (1996) 855
Comparative diagnostics of ArF- and KrF-laser generated carbon plumes used for amorphous diamond-like carbon film deposition, A.A. Puretzky, D.B. Geohegan, G.E. Jellison Jr. and M.M. McGibbon 96–98 (1996) 859
Carbon nitride thin films obtained by laser ablation of graphite in a nitrogen plasma, M.C. Polo, R. Aguiar, P. Serra, L. Clèries, M. Varela and J. Esteve 96–98 (1996) 870
Structural and optical characteristics of pulsed laser deposited ZnSe epilayers, A. Chergui, J.L. Deiss, J.B. Grun, J.L. Loison, M. Robino and R. Beserman 96–98 (1996) 874
Deposition of HgCdTe epitaxial layers on anisotropically etched silicon surfaces by laser evaporation, T.Ya. Gorbach, M. Kuźma, E. Sheregii, P.S. Smertenko, S.V. Svechnikov and G. Wisz 96–98 (1996) 881
Pulsed Laser Deposition of permanent magnetic $Nd_2Fe_{14}B$ thin films, A.J.M. Geurtsen, J.C.S. Kools, L. de Wit and J.C. Lodder 96–98 (1996) 887

Quartz

Multiwavelength irradiation effect in fused quartz ablation using vacuum-ultraviolet Raman laser, K. Sugioka, S. Wada, Y. Ohnuma, A. Nakamura, H. Tashiro and K. Toyoda 96–98 (1996) 347

Raman scattering

Multiwavelength irradiation effect in fused quartz ablation using vacuum-ultraviolet Raman laser, K. Sugioka, S. Wada, Y. Ohnuma, A. Nakamura, H. Tashiro and K. Toyoda 96–98 (1996) 347
Micro-Raman study of UV laser ablation of GaAs and Si substrates, C. García, J. Ramos, A.C. Prieto, J. Jiménez, C. Geertsen, J.L. Lacour and P. Mauchien 96–98 (1996) 370
Laser cleaning in art restoration, I. Gobernado-Mitre, J. Medina, B. Calvo, A.C. Prieto, L.A. Leal, B. Pérez, F. Marcos and A.M. de Frutos 96–98 (1996) 474
Preparation of TiO_2 thin films by pulsed laser deposition for waveguiding applications, C. Garapon, C. Champeaux, J. Mugnier, G. Panczer, P. Marchet, A. Catherinot and B. Jacquier 96–98 (1996) 836

Pulsed laser deposition of electroceramic thin films, M. Mertin, D. Offenberg, C.W. An, D.A. Wesner and E.W. Kreutz 96–98 (1996) 842

Rare earth metals

Rare-earth doped glass waveguides prepared by pulsed laser deposition, C.N. Afonso, J.M. Ballesteros, J. Gonzalo, G.C. Righini and S. Pelli 96–98 (1996) 760

Scanning tunneling microscopy

Ultrathin film deposition by pulsed laser ablation using crossed beams, A.A. Gorbunov, W. Pompe, A. Sewing, S.V. Gaponov, A.D. Akhsakhalyan, I.G. Zabrodin, I.A. Kas'kov, E.B. Klyenkov, A.P. Morozov, N.N. Salaschenko, R. Dietsch, H. Mai and S. Völlmar 96–98 (1996) 649

Improved properties of Pulsed Laser Deposited YBaCuO on $NdGaO_3$ using CeO_2 template layers, D.H.A. Blank, A.J.H.M. Rijnders, F.J.G. Roesthuis, G. den Ouden and H. Rogalla 96–98 (1996) 685

Secondary ion mass spectrometry

Chemical surface modification of fluorocarbon polymers by excimer laser processing, H. Niino and A. Yabe 96–98 (1996) 550

Semiconductors

Laser beam application to thin film transistors, T. Sameshima 96–98 (1996) 352

Electrical characterization of semiconducting La doped $SrTiO_3$ thin films prepared by pulsed laser deposition, K.-O. Grosse-Holz, J.F.M. Cillessen and R. Waser 96–98 (1996) 784

Silicon

Analytical description of the film thickness distribution obtained by the pulsed laser ablation of a monoatomic target: application to silicon and germanium, F. Antoni, C. Fuchs and E. Fogarassy 96–98 (1996) 50

Electromagnetic diagnostics during pulsed laser deposition, A.V. Kabashin, W. Marine, P.I. Nikitin and M. Sentis 96–98 (1996) 139

Temperature measurements during laser ablation of Si into He, Ar and O_2, H.C. Le, R.W. Dreyfus, W. Marine, M. Sentis and I.A. Movtchan 96–98 (1996) 164

Dynamics of silicon plume generated by laser ablation and its chemical reaction, T. Makimura and K. Murakami 96–98 (1996) 242

Optical spectroscopy of emission from Si–SiO_x nanoclusters formed by laser ablation, I.A. Movtchan, W. Marine, R.W. Dreyfus, H.C. Le, M. Sentis and M. Autric 96–98 (1996) 251

Micro-Raman study of UV laser ablation of GaAs and Si substrates, C. García, J. Ramos, A.C. Prieto, J. Jiménez, C. Geertsen, J.L. Lacour and P. Mauchien 96–98 (1996) 370

Single shot excimer laser annealing of amorphous silicon for AMLCD, P. Boher, J.L. Stehle, M. Stehle and B. Godard 96–98 (1996) 376

Photon-induced dry etching of Si(100) in the VUV, U. Streller, B. Li, A. Krabbe and N. Schwentner 96–98 (1996) 448

Laser-induced formation of visible light emitting silicon, D. Dimova-Malinovska, M. Tzolov, N. Malinowski, Ts. Marinova and V. Krastev 96–98 (1996) 457

CCl_4-assisted CF_4 etching of silicon in a microwave-assisted LDE (laser dry etching)-process, W. Pfleging, D.A. Wesner and E.W. Kreutz 96–98 (1996) 496

White synchrotron X-radiation-section topography of high energy density ns-pulsed (Nd:YAG) ablation damage in Si(100) wafers, J.D. Stephenson 96–98 (1996) 528

Preparation of SiO_xN_y films by reactive KrF laser ablation, K. Maruyama, Y. Aoki, M. Matsumoto, Y. Hiroshima and H. Ohta 96–98 (1996) 764

Silicon carbide

Excimer laser-induced hydrodynamical effects and surface modifications on silicon carbide, G. Nicolas and M. Autric 96–98 (1996) 296

Excimer laser induced thermal evaporation and ablation of silicon carbide, R. Reitano, P. Baeri and N. Marino 96–98 (1996) 302

Laser reactive ablation deposition of silicon carbide films, G. Leggieri, A. Luches, M. Martino, A. Perrone, R. Alexandrescu, A. Barborica, E. Gyorgy, I.N. Mihailescu, G. Majni and P. Mengucci 96–98 (1996) 866

Silicon oxide

Optical spectroscopy of emission from Si–SiO_x nanoclusters formed by laser ablation, I.A. Movtchan, W. Marine, R.W. Dreyfus, H.C. Le, M. Sentis and M. Autric 96–98 (1996) 251

Silver

Ablation from metals induced by visible and UV laser irradiation, W. Svendsen, J. Schou, B. Thestrup and O. Ellegaard 96–98 (1996) 518

Sputter deposition

Low-fluence excimer laser irradiation-induced defect formation in indium–tin oxide films, T. Szörényi, L.D. Laude, I. Bertóti, Zs. Geretovszky and Z. Kántor 96–98 (1996) 363

Sputtering

Comments on explosive mechanisms of laser sputtering, R. Kelly and A. Miotello 96–98 (1996) 205

Sulphides

XeCl laser ablation of thin film ZnS, W.M. Cranton, P.H. Key, D. Sands, C.B. Thomas and F.X. Wagner 96–98 (1996) 501

Superconductivity

Spectroscopic study of the microwave plasma enhanced pulsed laser deposition for $Y_1Ba_2Cu_3O_{7-x}$ superconducting thin films, B.C. Chung, C.H. Tsai, S.S. Hsu, C.S. Huang, T.Y. Tseng and I.N. Lin 96–98 (1996) 233

Single crystal laser patterning for selective $YBa_2Cu_3O_{7-x}$ growth, R. Aguiar, F. Sánchez and M. Varela 96–98 (1996) 405

Formation of artificially-layered high-temperature superconductors using pulsed-laser deposition, D.P. Norton, B.C. Chakoumakos, D.H. Lowndes and J.D. Budai 96–98 (1996) 672

Stoichiometric transfer of complex oxides by pulsed laser deposition, B. Dam, J.H. Rector, J. Johansson, S. Kars and R. Griessen 96–98 (1996) 679

Improved properties of Pulsed Laser Deposited YBaCuO on $NdGaO_3$ using CeO_2 template layers, D.H.A. Blank, A.J.H.M. Rijnders, F.J.G. Roesthuis, G. den Ouden and H. Rogalla 96–98 (1996) 685

Giant laser-induced voltages at room temperature in Pr doped Y–Ba–Cu–O thin films, H.-U. Habermeier, N. Jisrawi and G. Jäger-Waldau 96–98 (1996) 689

The importance of gas scattering processes on the stoichiometry deviations of laser deposited films, J. Gonzalo, C.N. Afonso, J. Perrière and R. Gómez San Roman 96–98 (1996) 693

Critical thickness of YBaCuO (123) strained thin films and superlattices grown by pulsed laser deposition, A. Abert, J.P. Contour, A. Défossez, D. Ravelosona, W. Schwegle and P. Ziemann 96–98 (1996) 703

Laser deposition of $YBa_2Cu_3O_7$ films on MgO(100) at 100 mm target–substrate distance and oxygen pressures below 0.1 mbar, F. Goerke, A. Thorns and U. Merkt 96–98 (1996) 708

Anisotropic resistivity in pulsed-laser deposited $Bi_2Sr_2CaCu_2O_{8+\delta}$ films, S.T. Li, A. Ritzer, S. Proyer, E. Stangl, D. Bäuerle and N. Reschauer 96–98 (1996) 713

Substrate size effect at off-axis laser deposition of multicomponent films, M.R. Predtechensky, O.M. Tukhto, A.N. Smal' and S.A. Vasil'eva 96–98 (1996) 717

In-situ reflectivity measurements during pulsed-laser deposition of $Bi_2Sr_2CaCu_2O_{8+\delta}$, A. Ritzer, B. Falkner, S.T. Li and D. Bäuerle 96–98 (1996) 721

Ion-assisted pulsed-laser deposition for the fabrication of Y–Ba–Cu–O multilayer structures using oriented intermediate layers of YSZ and CeO_2, R.P. Reade and R.E. Russo 96–98 (1996) 726

Synthesis of RE–Ba–Sr–Cu–O by pulsed-laser deposition, E. Stangl, S. Proyer, B. Hellebrand and D. Bäuerle 96–98 (1996) 731

Mirror-smooth $YBa_2Cu_3O_{7-x}$ superconducting films deposited by plasma-enhanced pulsed laser deposition technique, C.S. Huang, T.Y. Tseng, B.C. Chung, C.H. Tsai, H.F. Cheng and I.N. Lin 96–98 (1996) 735

Reactive laser deposition of high quality YBaCuO and ErBaCuO films, D. Berling, A. Del Vecchio, S. Acquaviva, D. Bolmont, G. Leggieri, B. Loegel, M. Luisa De Giorgi, A. Luches, A. Mehdaoui and L. Tapfer 96–98 (1996) 739

Superlattices

Formation of artificially-layered high-temperature superconductors using pulsed-laser deposition, D.P. Norton, B.C. Chakoumakos, D.H. Lowndes and J.D. Budai 96–98 (1996) 672

Critical thickness of YBaCuO (123) strained thin films and superlattices grown by pulsed laser deposition, A. Abert, J.P. Contour, A. Défossez, D. Ravelosona, W. Schwegle and P. Ziemann 96–98 (1996) 703

Surface conductivity

Classification of particulates on pulsed-laser deposited Y–Ba–Cu–O films, S. Proyer, E. Stangl, M. Borz and D. Bäuerle 96–98 (1996) 668

Tantalum

Off-axis excimer laser deposition of Ta_2O_5 thin films, N. Inoue, S. Kashiwabara, S. Toshima and R. Fujimoto 96–98 (1996) 656

Tellurium

Time-of-flight characterization of laser ablation plume from $NbTe_2$ target in He atmosphere, F. Grangeon, H. Sassoli, W. Marine and M. Autric 96–98 (1996) 186

Investigation of vaporization and condensation processes of thin layers of CdHgTe from laser erosion plasma in Hg atmosphere, B.K. Kotlyarchuk, D.I. Popovych, V.K. Savchuk and V.G. Savitsky 96–98 (1996) 192

Deposition of HgCdTe epitaxial layers on anisotropically etched silicon surfaces by laser evaporation, T.Ya. Gorbach, M. Kuźma, E. Sheregii, P.S. Smertenko, S.V. Svechnikov and G. Wisz 96–98 (1996) 881

Thin films

Analytical description of the film thickness distribution obtained by the pulsed laser ablation of a monoatomic target: application to silicon and germanium, F. Antoni, C. Fuchs and E. Fogarassy 96–98 (1996) 50

Plasma parameters in pulsed laser-plasma deposition of thin films, S. Metev, M. Ozegowski, G. Sepold and S. Burmester 96–98 (1996) 122

Investigation of vaporization and condensation processes of thin layers of CdHgTe from laser erosion plasma in Hg atmosphere, B.K. Kotlyarchuk, D.I. Popovych, V.K. Savchuk and V.G. Savitsky 96–98 (1996) 192

Optical and particle properties of PLD vapour/plasmas of ceramics, M. Alunovic, H. Stamm, M. Aden and E.W. Kreutz 96–98 (1996) 222

Spectroscopic study of the microwave plasma enhanced pulsed laser deposition for $Y_1Ba_2Cu_3O_{7-x}$ superconducting thin films, B.C. Chung, C.H. Tsai, S.S. Hsu, C.S. Huang, T.Y. Tseng and I.N. Lin 96–98 (1996) 233

Laser patterning of thin-film electrochemical gas sensors, A. Lecours, M. Caron, P. Ciureanu, G. Turcotte, D. Ivanov, A. Yelon and J.F. Currie 96–98 (1996) 341

Laser beam application to thin film transistors, T. Sameshima 96–98 (1996) 352

Low-fluence excimer laser irradiation-induced defect formation in indium–tin oxide films, T. Szörényi, L.D. Laude, I. Bertóti, Zs. Geretovszky and Z. Kántor 96–98 (1996) 363

Liquid carbon observed with reflection measurements on CVD-diamond under UV pulsed-laser irradiation, P. Tosin, W. Lüthy and H.P. Weber 96–98 (1996) 384

Excimer laser interaction with dielectric thin films, E. Welsch, K. Ettrich, H. Blaschke and N. Kaiser 96–98 (1996) 393

Decomposition mechanisms of thin palladium acetate film with excimer UV radiation, J.-Y. Zhang, H. Esrom and I.W. Boyd 96–98 (1996) 399

Single crystal laser patterning for selective $YBa_2Cu_3O_{7-x}$ growth, R. Aguiar, F. Sánchez and M. Varela 96–98 (1996) 405

Picosecond UV-laser ablation of Au and Ni films, A. Rosenfeld and E.E.B. Campbell 96–98 (1996) 439

XeCl laser ablation of thin film ZnS, W.M. Cranton, P.H. Key, D. Sands, C.B. Thomas and F.X. Wagner 96–98 (1996) 501

Surface temperature measurements during pulsed laser action on metallic and ceramic materials, M.B. Ignatiev, I.Yu. Smurov, G. Flamant and V.N. Senchenko 96–98 (1996) 505

Surface chemical reaction of polymer film with reactive intermediates produced by laser ablation of azido compound, H. Niino and A. Yabe 96–98 (1996) 572

Pulsed laser ablation and deposition of fluorocarbon polymers, M.G. Norton, W. Jiang, J.T. Dickinson and K.W. Hipps 96–98 (1996) 617

Deposition of fluoropolymer thin films containing semiconductor microcrystallites by VUV laser ablation, T. Fujii, S. Inoue and F. Kannari 96–98 (1996) 621

Electrical and optical characteristics of organic thin films fabricated by laser ablation, T. Fujii, H. Shima, N. Matsumoto and F. Kannari 96–98 (1996) 625

Thin film growth by the pulsed laser assisted deposition technique, C. Belouet 96–98 (1996) 630

Scale-up of pulsed laser deposition (PLD) for 4″-wafer coating, M. Panzner, R. Dietsch, Th. Holz, H. Mai and S. Völlmar 96–98 (1996) 643

Ultrathin film deposition by pulsed laser ablation using crossed beams, A.A. Gor-

bunov, W. Pompe, A. Sewing, S.V. Gaponov, A.D. Akhsakhalyan, I.G. Zabrodin, I.A. Kas'kov, E.B. Klyenkov, A.P. Morozov, N.N. Salaschenko, R. Dietsch, H. Mai and S. Völlmar 96–98 (1996) 649

Off-axis excimer laser deposition of Ta_2O_5 thin films, N. Inoue, S. Kashiwabara, S. Toshima and R. Fujimoto 96–98 (1996) 656

Classification of particulates on pulsed-laser deposited Y–Ba–Cu–O films, S. Proyer, E. Stangl, M. Borz and D. Bäuerle 96–98 (1996) 668

Formation of artificially-layered high-temperature superconductors using pulsed-laser deposition, D.P. Norton, B.C. Chakoumakos, D.H. Lowndes and J.D. Budai 96–98 (1996) 672

Stoichiometric transfer of complex oxides by pulsed laser deposition, B. Dam, J.H. Rector, J. Johansson, S. Kars and R. Griessen 96–98 (1996) 679

Improved properties of Pulsed Laser Deposited YBaCuO on $NdGaO_3$ using CeO_2 template layers, D.H.A. Blank, A.J.H.M. Rijnders, F.J.G. Roesthuis, G. den Ouden and H. Rogalla 96–98 (1996) 685

The importance of gas scattering processes on the stoichiometry deviations of laser deposited films, J. Gonzalo, C.N. Afonso, J. Perrière and R. Gómez San Roman 96–98 (1996) 693

Laser ablation of oxides: study of the oxygen incorporation by ^{18}O isotopic tracing techniques, R. Pérez Casero, R. Gómez San Román, C. Maréchal, J.P. Enard and J. Perrière 96–98 (1996) 697

Critical thickness of YBaCuO (123) strained thin films and superlattices grown by pulsed laser deposition, A. Abert, J.P. Contour, A. Défossez, D. Ravelosona, W. Schwegle and P. Ziemann 96–98 (1996) 703

Laser deposition of $YBa_2Cu_3O_7$ films on MgO(100) at 100 mm target–substrate distance and oxygen pressures below 0.1 mbar, F. Goerke, A. Thorns and U. Merkt 96–98 (1996) 708

Anisotropic resistivity in pulsed-laser deposited $Bi_2Sr_2CaCu_2O_{8+\delta}$ films, S.T. Li, A. Ritzer, S. Proyer, E. Stangl, D. Bäuerle and N. Reschauer 96–98 (1996) 713

Substrate size effect at off-axis laser deposition of multicomponent films, M.R. Predtechensky, O.M. Tukhto, A.N. Smal' and S.A. Vasil'eva 96–98 (1996) 717

In-situ reflectivity measurements during pulsed-laser deposition of $Bi_2Sr_2CaCu_2O_{8+\delta}$, A. Ritzer, B. Falkner, S.T. Li and D. Bäuerle 96–98 (1996) 721

Ion-assisted pulsed-laser deposition for the fabrication of Y–Ba–Cu–O multilayer structures using oriented intermediate layers of YSZ and CeO_2, R.P. Reade and R.E. Russo 96–98 (1996) 726

Synthesis of RE–Ba–Sr–Cu–O by pulsed-laser deposition, E. Stangl, S. Proyer, B. Hellebrand and D. Bäuerle 96–98 (1996) 731

Mirror-smooth $YBa_2Cu_3O_{7-x}$ superconducting films deposited by plasma-enhanced pulsed laser deposition technique, C.S. Huang, T.Y. Tseng, B.C. Chung, C.H. Tsai, H.F. Cheng and I.N. Lin 96–98 (1996) 735

Growth, structuring and characterisation of all-oxide thin film devices prepared by pulsed laser deposition, J.F.M. Cillessen, R.M. Wolf, J.B. Giesbers, P.W.M. Blom, K.-O. Grosse-Holz and E. Pastoor 96–98 (1996) 744

Deposition of optical coatings by pulsed laser ablation, G. Reisse, S. Weissmantel, B. Keiper and U. Broulik 96–98 (1996) 752

Rare-earth doped glass waveguides prepared by pulsed laser deposition, C.N. Afonso, J.M. Ballesteros, J. Gonzalo, G.C. Righini and S. Pelli 96–98 (1996) 760

Preparation of SiO_xN_y films by reactive KrF laser ablation, K. Maruyama, Y. Aoki, M. Matsumoto, Y. Hiroshima and H. Ohta 96–98 (1996) 764

Kinetic energy distributions of ions ejected during laser ablation of lead zirconate titanate and their correlation to deposition of ferroelectric thin films, G.C. Tyrrell, T.H. York, L.G. Coccia and I.W. Boyd 96–98 (1996) 769

Epitaxial ferroelectric PZT and BST thin films by pulsed UV laser deposition, C. Champeaux, P. Marchet and A. Catherinot 96–98 (1996) 775

Growth and characterization of PLZT films, M.J.M. Gomes, E. de Matos Gomes, P.L.Q. Mantas and J.L. Baptista 96–98 (1996) 779

Pulsed laser deposition of sillenite films intended for photorefractive damage free waveguides, J.E. Alfonso, M.J. Martín, J. Mendiola, K. Polgár and C. Zaldo 96–98 (1996) 791

Ferrimagnetic thin films prepared by pulsed laser deposition, M. Guyot, A. Lisfi, R. Krishnan, M. Porte, P. Rougier and V. Cagan 96–98 (1996) 802

Pulsed laser deposition of high quality ITO thin films, F. Hanus, A. Jadin and L.D. Laude 96–98 (1996) 807

Pulsed-laser deposited ZnO for device applications, S.L. King, J.G.E. Gardeniers and I.W. Boyd 96–98 (1996) 811

Excimer laser ablating preparation of $Ba_2NaNb_5O_{15}$ thin films on $KTiOPO_4$ substrate and its guide wave property, J.M. Liu, Z.G. Liu, S.N. Zhu, Y.Y. Zhu and N.B. Ming 96–98 (1996) 819
$Pb_{1-x}Ca_xTiO_3$ thin films prepared by laser ablation of ceramic targets, M.J. Martín, C. Zaldo and J. Mendiola 96–98 (1996) 823
Characterization of ZnO thin films deposited by laser ablation in reactive atmosphere, P. Verardi, M. Dinescu and A. Andrei 96–98 (1996) 827
An experimental study and modeling of the thickness distribution in pulsed laser deposited ferroelectric thin films, M. Tyunina, K. Sreenivas, C. Bjormander, J. Wittborn and K.V. Rao 96–98 (1996) 831
Pulsed laser deposition of electroceramic thin films, M. Mertin, D. Offenberg, C.W. An, D.A. Wesner and E.W. Kreutz 96–98 (1996) 842
Excimer laser ablation and film deposition of Ti:sapphire, P.E. Dyer, S.R. Jackson, P.H. Key, W.J. Metheringham and M.J.J. Schmidt 96–98 (1996) 849
Pulsed laser deposition of nasicon thin films, R. Izquierdo, F. Hanus, Th. Lang, D. Ivanov, M. Meunier, L. Laude, J.F. Currie and A. Yelon 96–98 (1996) 855
Comparative diagnostics of ArF- and KrF-laser generated carbon plumes used for amorphous diamond-like carbon film deposition, A.A. Puretzky, D.B. Geohegan, G.E. Jellison Jr. and M.M. McGibbon 96–98 (1996) 859
Carbon nitride thin films obtained by laser ablation of graphite in a nitrogen plasma, M.C. Polo, R. Aguiar, P. Serra, L. Clèries, M. Varela and J. Esteve 96–98 (1996) 870
Deposition of HgCdTe epitaxial layers on anisotropically etched silicon surfaces by laser evaporation, T.Ya. Gorbach, M. Kuźma, E. Sheregii, P.S. Smertenko, S.V. Svechnikov and G. Wisz 96–98 (1996) 881
Pulsed Laser Deposition of permanent magnetic $Nd_2Fe_{14}B$ thin films, A.J.M. Geurtsen, J.C.S. Kools, L. de Wit and J.C. Lodder 96–98 (1996) 887

Time of flight techniques

Modeling of laser induced plasma, spectroscopic and time of flight experiments in pulsed laser deposition, G. Granse, S. Völlmar, A. Lenk, A. Rupp and K. Rohr 96–98 (1996) 97
Transport of neutral atoms, monoxides and clusters in the plume produced by laser ablation of $YBa_2Cu_3O_{7-x}$ in oxygen environment, A.V. Bulgakov, M.R. Predtechensky and A.P. Mayorov 96–98 (1996) 159
Laser produced plasmas in high fluence ablation of metallic surfaces probed by time-of-flight mass spectrometry, S. Amoruso, A. Amodeo, V. Berardi, R. Bruzzese, N. Spinelli and R. Velotta 96–98 (1996) 175
Time-of-flight characterization of laser ablation plume from $NbTe_2$ target in He atmosphere, F. Grangeon, H. Sassoli, W. Marine and M. Autric 96–98 (1996) 186
Soft laser sputtering of the GaAlAs (100) surface, L. Vivet, B. Dubreuil, T. Gibert-Legrand and M.F. Barthe 96–98 (1996) 238
Optical spectroscopy of emission from Si–SiO_x nanoclusters formed by laser ablation, I.A. Movtchan, W. Marine, R.W. Dreyfus, H.C. Le, M. Sentis and M. Autric 96–98 (1996) 251
Magnetic field enhanced growth of carbon cluster ions in the laser ablation plume of graphite, F. Kokai, Y. Koga and R.B. Heimann 96–98 (1996) 261
The role of defects in laser induced positive ion emission from ionic crystals, J.T. Dickinson, J.-J. Shin and S.C. Langford 96–98 (1996) 316
Selection of kinetic energy of laser ablated particles, K. Kuba and T. Sugihara 96–98 (1996) 659

Tin oxide

Low-fluence excimer laser irradiation-induced defect formation in indium–tin oxide films, T. Szörényi, L.D. Laude, I. Bertóti, Zs. Geretovszky and Z. Kántor 96–98 (1996) 363
Pulsed laser deposition of high quality ITO thin films, F. Hanus, A. Jadin and L.D. Laude 96–98 (1996) 807

Titanium

$Pb_{1-x}Ca_xTiO_3$ thin films prepared by laser ablation of ceramic targets, M.J. Martín, C. Zaldo and J. Mendiola 96–98 (1996) 823

Titanium oxide

Preparation of TiO_2 thin films by pulsed laser deposition for waveguiding applications, C. Garapon, C. Champeaux, J. Mugnier, G. Panczer, P. Marchet, A. Catherinot and B. Jacquier 96–98 (1996) 836

Tungsten

In situ surface cleaning of pure and implanted tungsten photocathodes by pulsed laser irradiation, M. Afif, J.P. Girardeau-Montaut, C. Tomas, M. Romand, M. Charbonnier, N.S. Prakash, A. Perez, G. Marest and J.M. Frigerio 96–98 (1996) 469

X-ray absorption

Dynamics of silicon plume generated by laser ablation and its chemical reaction, T. Makimura and K. Murakami 96–98 (1996) 242

X-ray diffraction

Laser cleaning in art restoration, I. Gobernado-Mitre, J. Medina, B. Calvo, A.C. Prieto, L.A. Leal, B. Pérez, F. Marcos and A.M. de Frutos 96–98 (1996) 474

Electrical and optical characteristics of organic thin films fabricated by laser ablation, T. Fujii, H. Shima, N. Matsumoto and F. Kannari 96–98 (1996) 625

Off-axis excimer laser deposition of Ta_2O_5 thin films, N. Inoue, S. Kashiwabara, S. Toshima and R. Fujimoto 96–98 (1996) 656

Formation of artificially-layered high-temperature superconductors using pulsed-laser deposition, D.P. Norton, B.C. Chakoumakos, D.H. Lowndes and J.D. Budai 96–98 (1996) 672

Improved properties of Pulsed Laser Deposited YBaCuO on $NdGaO_3$ using CeO_2 template layers, D.H.A. Blank, A.J.H.M. Rijnders, F.J.G. Roesthuis, G. den Ouden and H. Rogalla 96–98 (1996) 685

Critical thickness of YBaCuO (123) strained thin films and superlattices grown by pulsed laser deposition, A. Abert, J.P. Contour, A. Défossez, D. Ravelosona, W. Schwegle and P. Ziemann 96–98 (1996) 703

Anisotropic resistivity in pulsed-laser deposited $Bi_2Sr_2CaCu_2O_{8+\delta}$ films, S.T. Li, A. Ritzer, S. Proyer, E. Stangl, D. Bäuerle and N. Reschauer 96–98 (1996) 713

Synthesis of RE–Ba–Sr–Cu–O by pulsed-laser deposition, E. Stangl, S. Proyer, B. Hellebrand and D. Bäuerle 96–98 (1996) 731

Mirror-smooth $YBa_2Cu_3O_{7-x}$ superconducting films deposited by plasma-enhanced pulsed laser deposition technique, C.S. Huang, T.Y. Tseng, B.C. Chung, C.H. Tsai, H.F. Cheng and I.N. Lin 96–98 (1996) 735

Reactive laser deposition of high quality YBaCuO and ErBaCuO films, D. Berling, A. Del Vecchio, S. Acquaviva, D. Bolmont, G. Leggieri, B. Loegel, M. Luisa De Giorgi, A. Luches, A. Mehdaoui and L. Tapfer 96–98 (1996) 739

Kinetic energy distributions of ions ejected during laser ablation of lead zirconate titanate and their correlation to deposition of ferroelectric thin films, G.C. Tyrrell, T.H. York, L.G. Coccia and I.W. Boyd 96–98 (1996) 769

Epitaxial ferroelectric PZT and BST thin films by pulsed UV laser deposition, C. Champeaux, P. Marchet and A. Catherinot 96–98 (1996) 775

Growth and characterization of PLZT films, M.J.M. Gomes, E. de Matos Gomes, P.L.Q. Mantas and J.L. Baptista 96–98 (1996) 779

Electrical characterization of semiconducting La doped $SrTiO_3$ thin films prepared by pulsed laser deposition, K.-O. Grosse-Holz, J.F.M. Cillessen and R. Waser 96–98 (1996) 784

Pulsed laser deposition of novel materials for thin film solid oxide fuel cell applications: $Ce_{0.9}Gd_{0.1}O_{1.95}$, $La_{0.7}Sr_{0.3}CoO_y$ and $La_{0.7}Sr_{0.3}Co_{0.2}Fe_{0.8}O_y$, L.G. Coccia, G.C. Tyrrell, J.A. Kilner, D. Waller, R.J. Chater and I.W. Boyd 96–98 (1996) 795

Ferrimagnetic thin films prepared by pulsed laser deposition, M. Guyot, A. Lisfi, R. Krishnan, M. Porte, P. Rougier and V. Cagan 96–98 (1996) 802

Pulsed laser deposition of high quality ITO thin films, F. Hanus, A. Jadin and L.D. Laude 96–98 (1996) 807

Pulsed-laser deposited ZnO for device applications, S.L. King, J.G.E. Gardeniers and I.W. Boyd 96–98 (1996) 811

Excimer laser ablating preparation of $Ba_2NaNb_5O_{15}$ thin films on $KTiOPO_4$ substrate and its guide wave property, J.M. Liu, Z.G. Liu, S.N. Zhu, Y.Y. Zhu and N.B. Ming 96–98 (1996) 819

$Pb_{1-x}Ca_xTiO_3$ thin films prepared by laser ablation of ceramic targets, M.J. Martín, C. Zaldo and J. Mendiola 96–98 (1996) 823

Preparation of TiO_2 thin films by pulsed laser deposition for waveguiding applications, C. Garapon, C. Champeaux, J. Mugnier, G. Panczer, P. Marchet, A. Catherinot and B. Jacquier 96–98 (1996) 836

Pulsed laser deposition of electroceramic thin films, M. Mertin, D. Offenberg, C.W. An, D.A. Wesner and E.W. Kreutz 96–98 (1996) 842

Laser reactive ablation deposition of silicon carbide films, G. Leggieri, A. Luches,

M. Martino, A. Perrone, R. Alexandrescu, A. Barborica, E. Gyorgy, I.N. Mihailescu, G. Majni and P. Mengucci 96–98 (1996) 866
Pulsed Laser Deposition of permanent magnetic $Nd_2Fe_{14}B$ thin films, A.J.M. Geurtsen, J.C.S. Kools, L. de Wit and J.C. Lodder 96–98 (1996) 887

X-ray emission

X-ray generation for medical applications from a laser-produced plasma, M. Grätz, C. Tillman, I. Mercer and S. Svanberg 96–98 (1996) 443

Zinc

Preferential vaporization and plasma shielding during nano-second laser ablation, X. Mao, W.-T. Chan, M. Caetano, M.A. Shannon and R.E. Russo 96–98 (1996) 126
XeCl laser ablation of thin film ZnS, W.M. Cranton, P.H. Key, D. Sands, C.B. Thomas and F.X. Wagner 96–98 (1996) 501

Zinc oxide

Pulsed-laser deposited ZnO for device applications, S.L. King, J.G.E. Gardeniers and I.W. Boyd 96–98 (1996) 811
Characterization of ZnO thin films deposited by laser ablation in reactive atmosphere, P. Verardi, M. Dinescu and A. Andrei 96–98 (1996) 827

Zinc selenide

Structural and optical characteristics of pulsed laser deposited ZnSe epilayers, A. Chergui, J.L. Deiss, J.B. Grun, J.L. Loison, M. Robino and R. Beserman 96–98 (1996) 874